

TrueTile modules & 4SBC Status & plans

Ringberg, 13.3.2019

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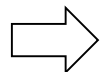
- Introduction
- The TrueTile concept
- 4SBC as TrueTile pathfinder
- System aspects of 4SBC
- MCC production
- 4SBC PCU development
- Summary & Outlook



Introduction

Project target:

- 4-side buttability allows for composite focal planes w/ large sensor area mosaic
- Design "platform/concept" for 4-side buttable integration of sensor devices
- Low sensitivity gap between modules
- Large composite focal planes
- Maximum degree of modularity
- Large power contingency
- Device independent / device tolerant



TrueTile concept



"I can't believe the pace of modern technology Ralph. A few-years ago, all these pictures would have been in black and white!"

TrueTile concept

- 4-side buttable sensor modules with minimal sensitivity gap
- 4 main "ingredients":
 - Make guardring structures as narrow as possible for small sensitivity gap
 - Use Active Interposer (AI) unit to host
 - MCC
 - Sensor
 - ASM"ish" structure with
 - ASICs
 - Supplementary drivers (BARD)
 - Passive circuitry
 - Accommodate all biasing and backend circuits within AI / Sensor envelope
 - Maximally modular approach

Rim concept (current proposal):

Optimized for minimal sensitive gap for 4 side buttability

Current values:

- 1.25 mm in column direction

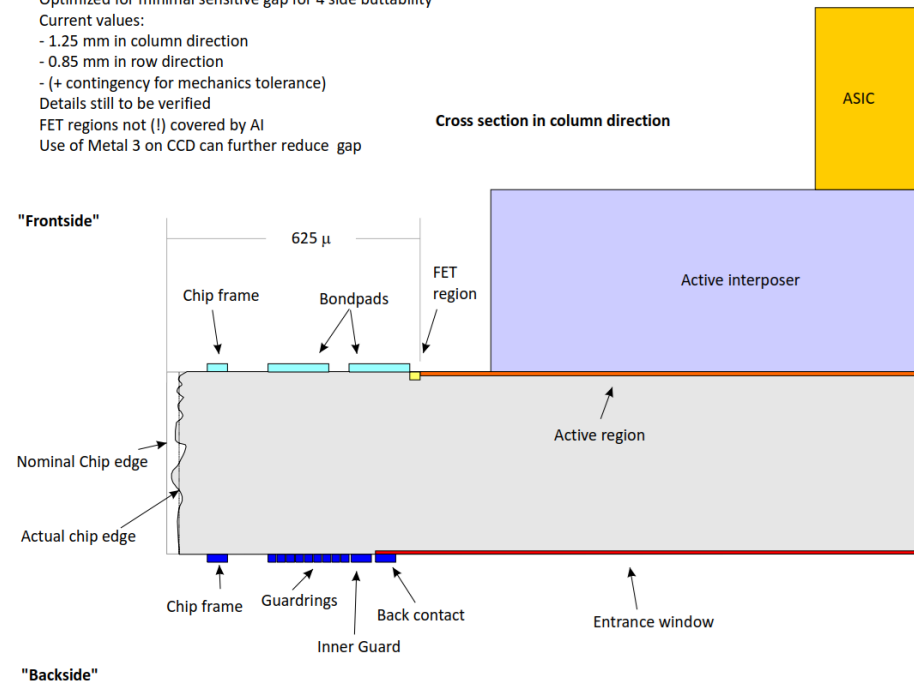
- 0.85 mm in row direction

- (+ contingency for mechanics tolerance)

Details still to be verified

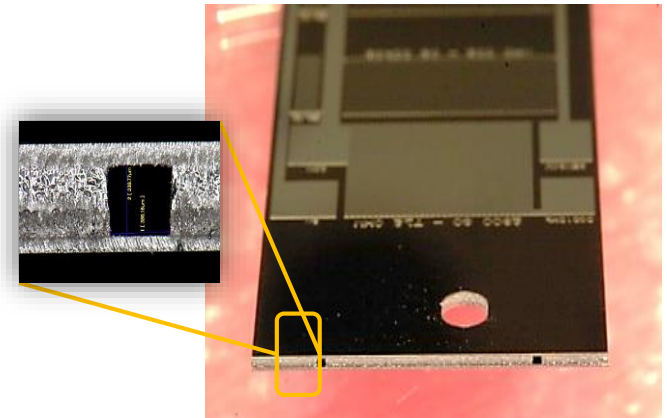
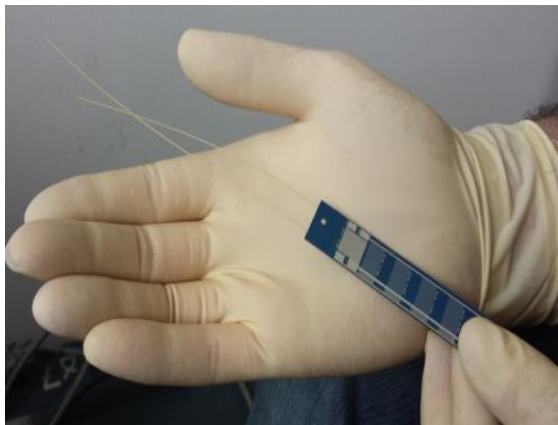
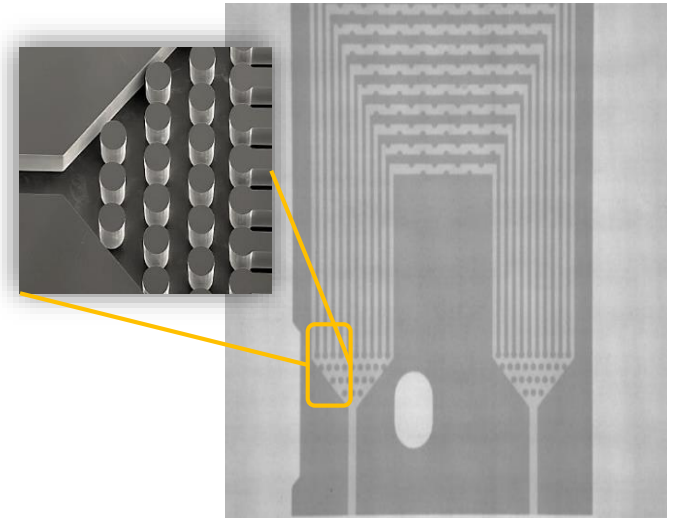
FET regions not (!) covered by AI

Use of Metal 3 on CCD can further reduce gap



TrueTile concept

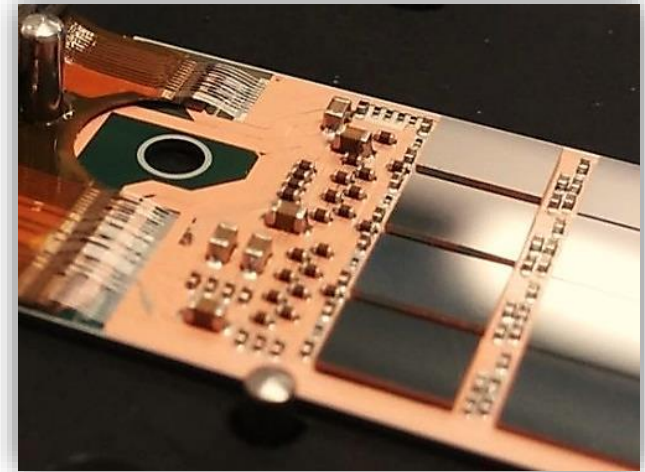
- **Microchannel cooler (MCC):**
 - Investigated as cooling concept for ATLAS / ILC
 - Plasma-etched channels in silicon wafer
 - Wafer bonded to lid wafer to hermetically seal channels
 - Channel design according to expected heat load distribution
 - Wafer can be processed like a normal wafer / lithography steps
 - Access to channels exposed during dicing



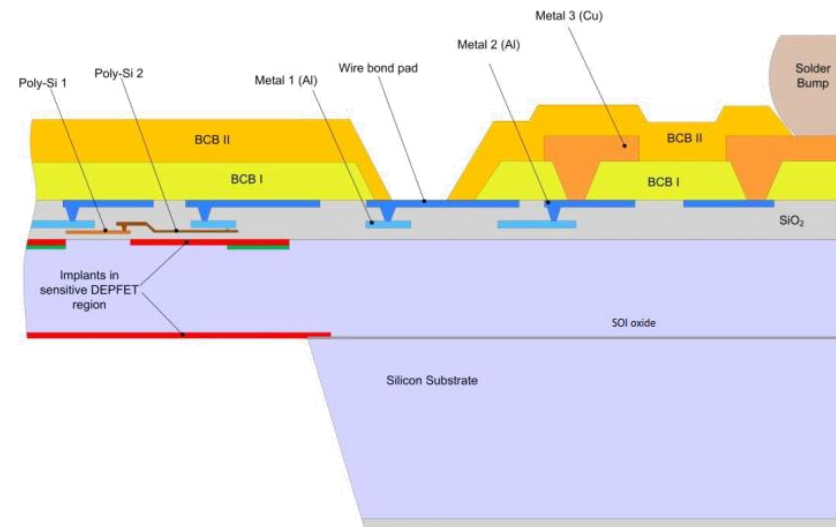
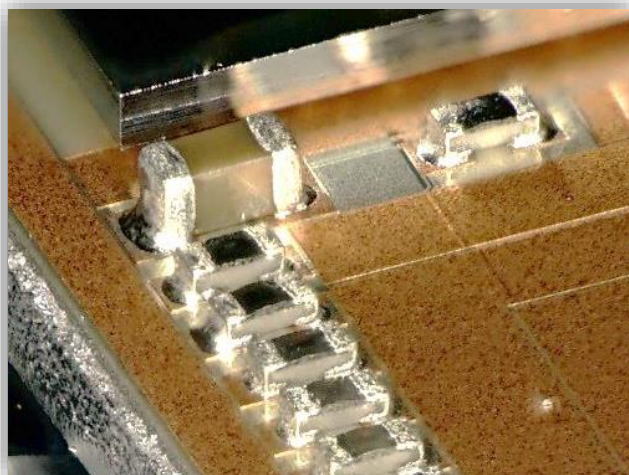
C. Marinas, Micro Channel Cooling for Tracking Detectors, Forum on Tracking Detector Mechanics, Bonn 2016

TrueTile concept

- **All-Silicon-Module (ASM):**
 - Sensor die includes regions for
 - Front-End-Electronics & Passives
 - Signal / Power traces
 - Bond-/Solderpads to periphery
 - "Passive" balcony regions, but no additional support structure



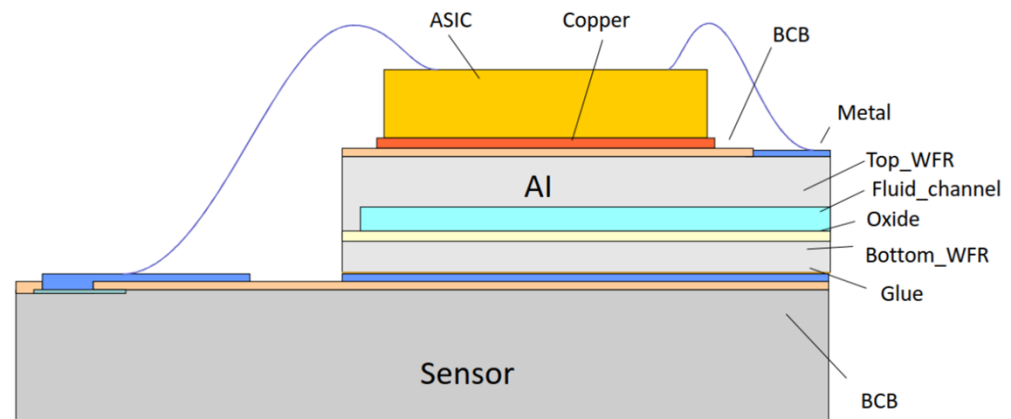
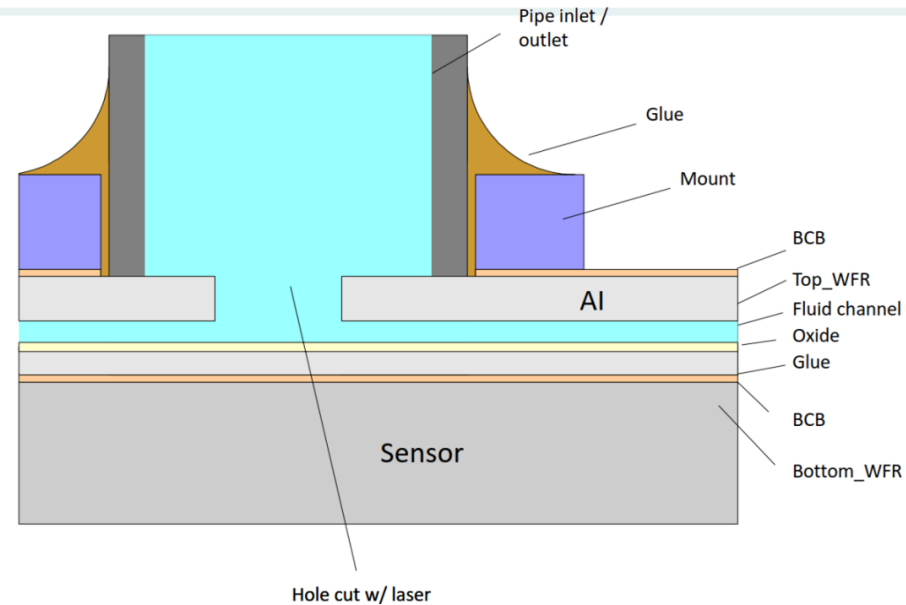
SuperBelle ASM on SOI wafer
w/ thinned sensor region



TrueTile concept

- **Active Interposer (AI):**

- Silicon interposer based on SOI:
 - Matchmaker / Pitchadapter to sensor die
 - Carrier for FE ASICs and passives
 - Carrier for peripheral connector
 - Substrate for power / signal trace system
 - Container for SOI based MCC
- Separated from sensor substrate
- Interface to support mechanics
- Fine-pitch 3-4 metal layer trace system
- μ Bump bond pads for FEE
- Optimum CTE match to sensor



Active Interposer (AI) approach

4SBC as TrueTile Pathfinder

Pathfinder device architecture:

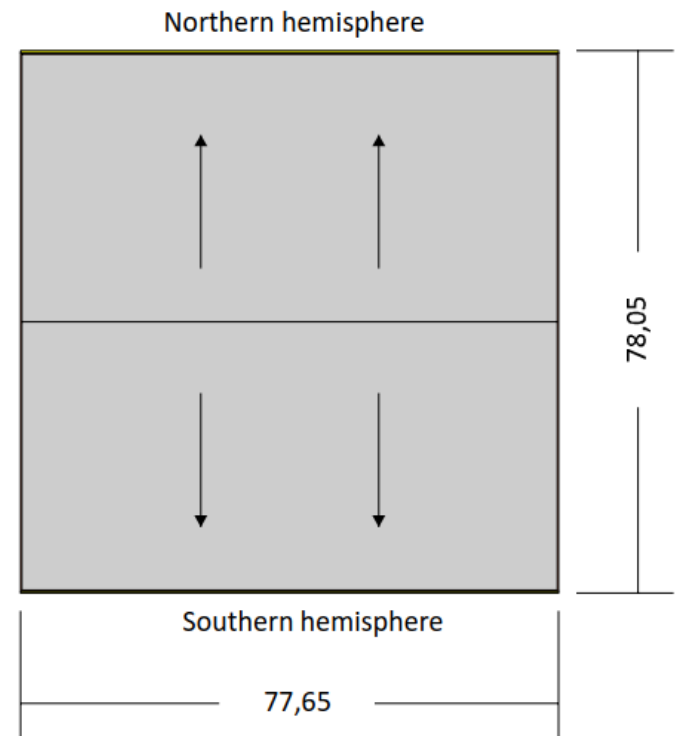
- "Conventional" pnCCD
- Standard mode (no frame store) suitable for synchronous operation
- Split frame / column parallel readout for optimized framerate
- 1 MPixel array with $75 \times 75 \mu\text{m}^2$ pixels, sensitive area $76.8 \times 76.8 \text{ mm}^2$
- 2 x 1024 JFET (north edge and south edge) readout nodes read in parallel
- Readout: 2 x 16 x 64 channels
- Low complexity, low turnaround time
- Manufacturing in progress

1024 x 1024 pixels

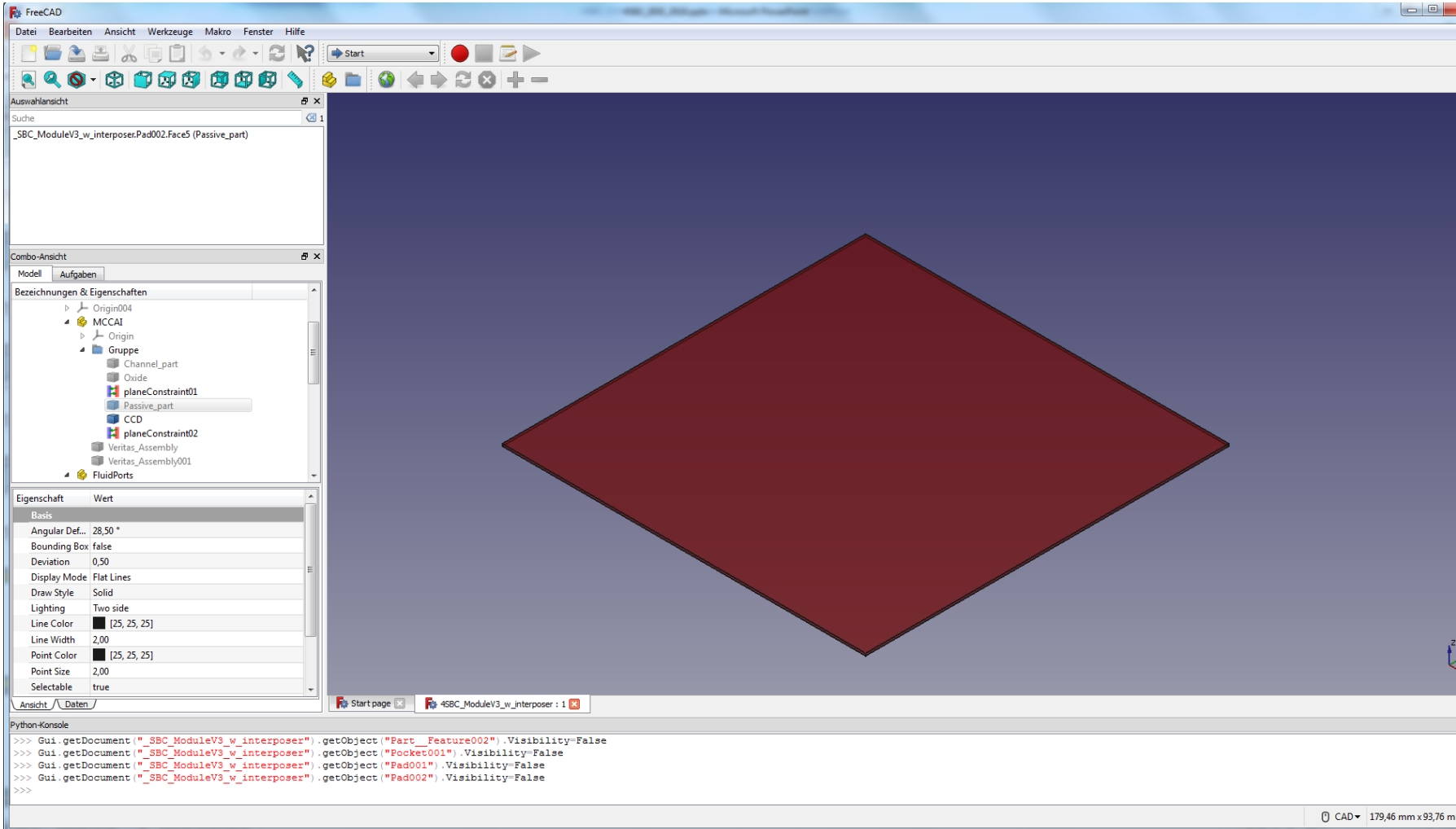
$75 \times 75 \mu\text{m}^2$

Sensitive area $76.8 \times 76.8 \text{ mm}^2$

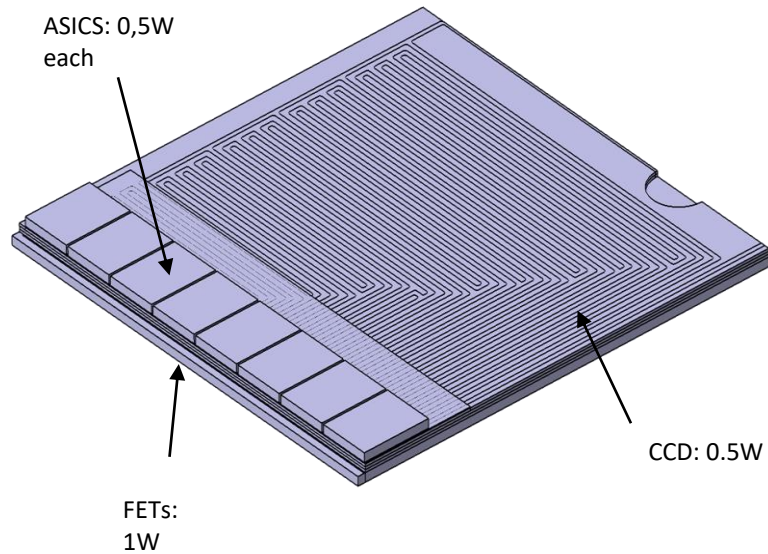
Standard mode, split frame, column-parallel pnCCD



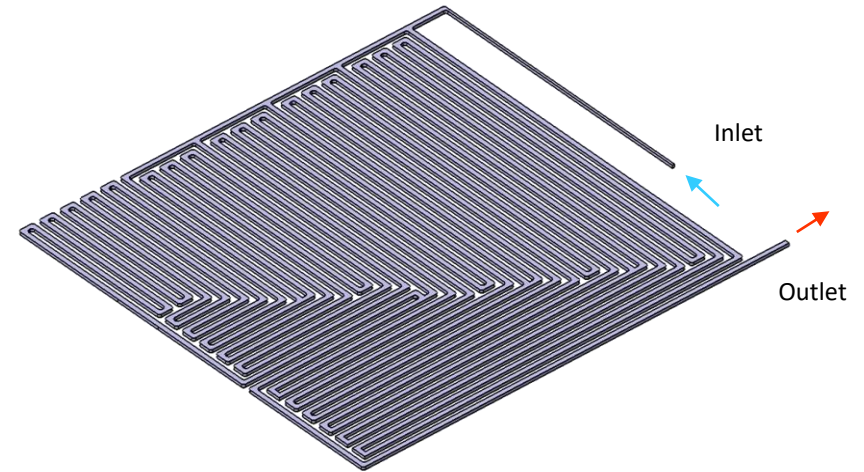
CCD



4SBC Pathfinder: MCC



Expected power dissipation



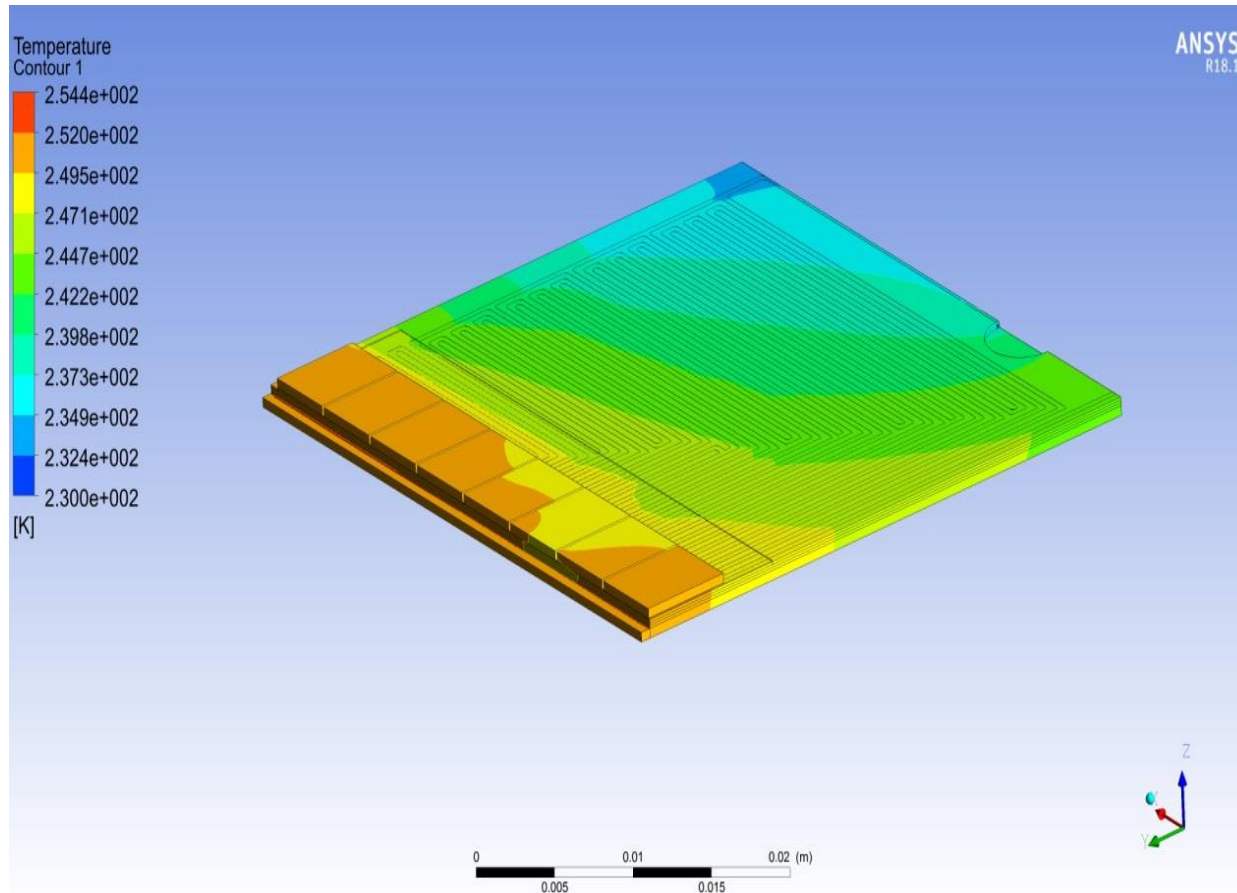
MCC channel design

Design and simulations:

M. Angel Villarejo, IFIC valencia

- 1 Quadrant of CCD
- Expected power dissipation
- Including parasitics (radiation, conductive contributions)

4SBC Pathfinder: MCC



$$P = c_p \cdot m \cdot \Delta T \rightarrow 7W = 1348 \times 2 \times 0,0002 \times 0,00015 \times 4077 \times (T_{out} - 230) \rightarrow 251K$$

Cooling fluid:

- PGW 80/20
- $\rho = 1.348 \text{ kg / l}$
- $\eta = 1.95 \text{ mPa s}$
- $c_p = 4077 \text{ J / kg K}$

T_{out} of fluid = 246K
 $\Delta P = 3 \text{ bar}$

Channel geometry
 $200 \times 150 \mu\text{m}^2$

Power dissipation
 @ MCC ~ 6 W
 @ Module ~ 25 W

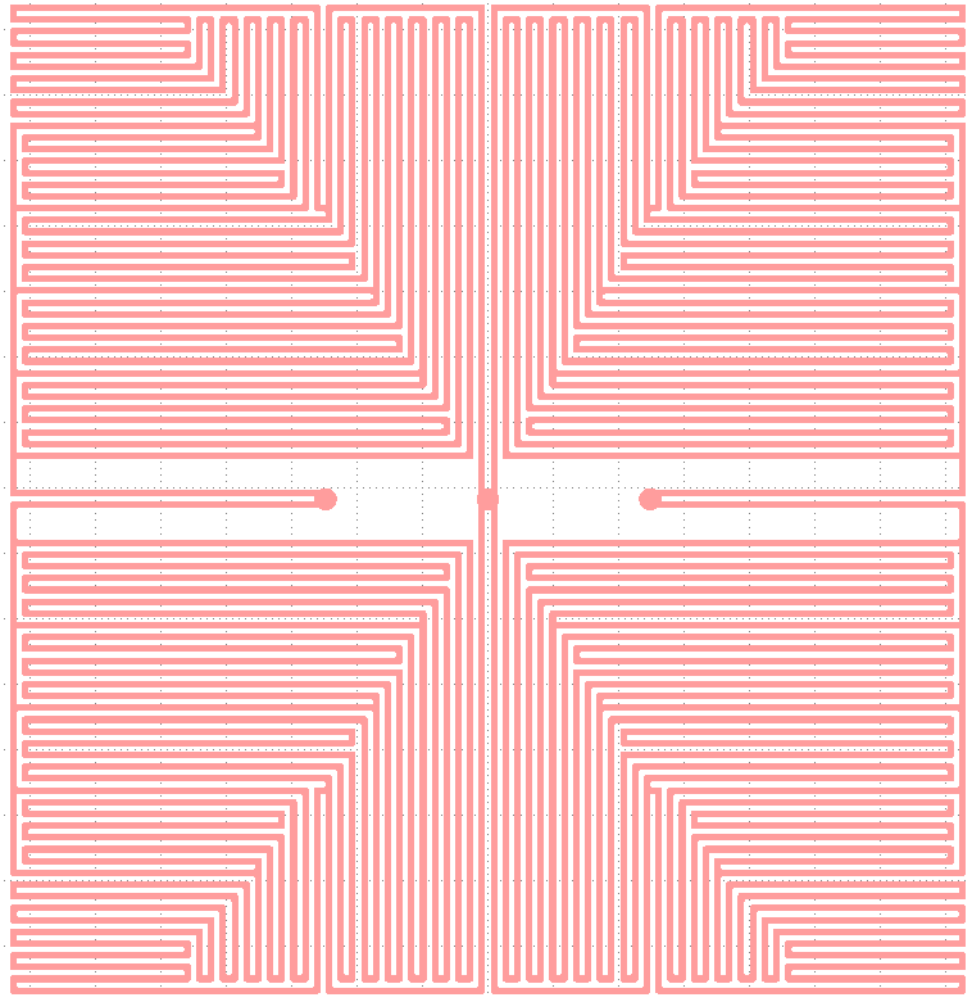
Temperature gradient
 on device ~ 15°

New channel geometry ($300 \mu\text{m}$)
 Adapted mass flow
 Temperature gradient
 on device $< 5^\circ \text{ C}$

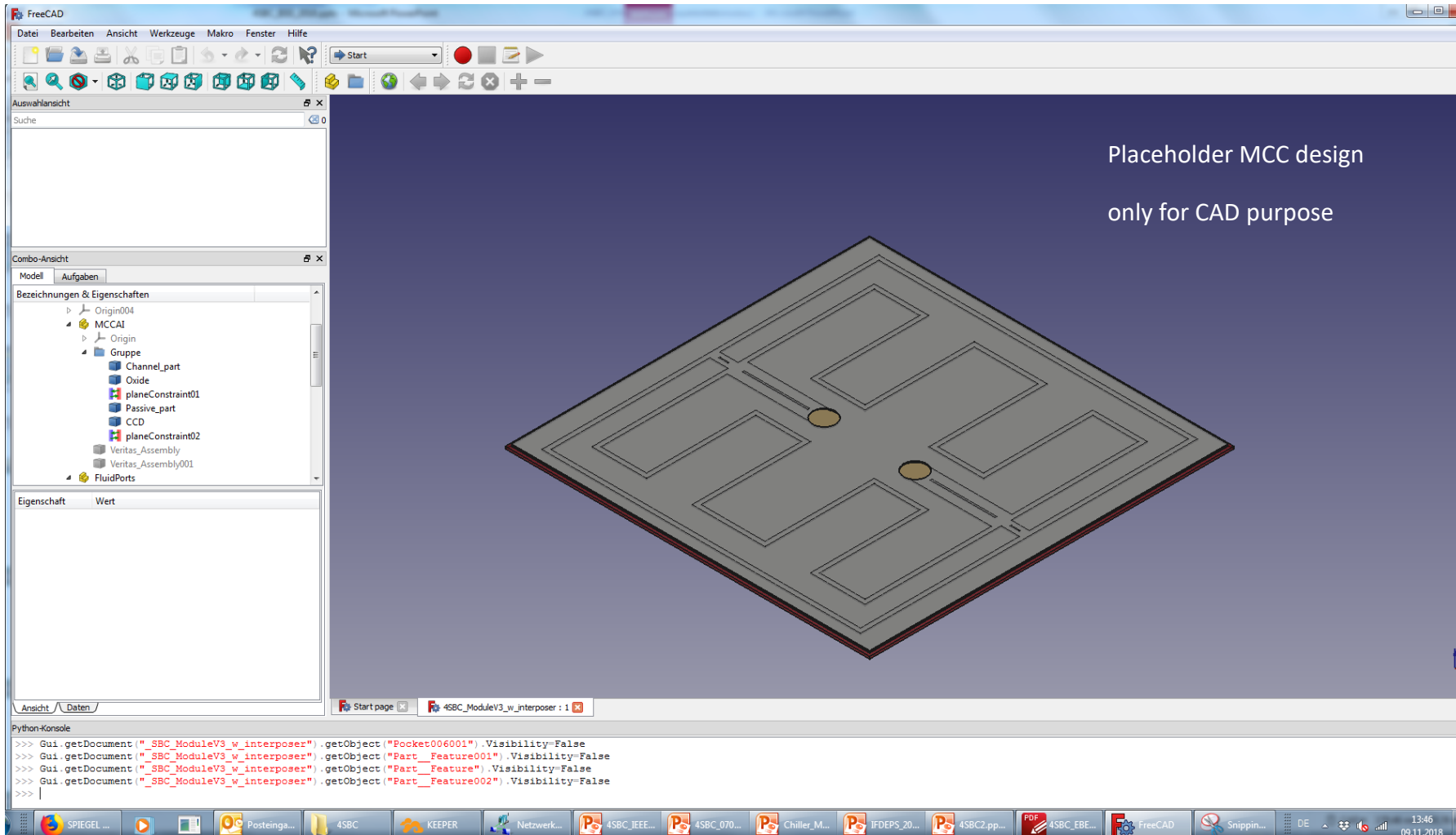
4SBC Pathfinder: MCC

MCC design:

- Large die area ($\sim 8 \times 8 \text{ cm}^2$) structure as base for 4SBC AI
- Used to furnish first 4SBC prototype systems
- Confirm thermal simulations
- 4 quadrants
- 2 inlets
- 1 central outlet



MCC



4SBC Pathfinder: Pipes & Tubing

Silicon Terminal:

- IDEX NanoPort assembly
- Material: PEEK, Pressure rating: 70 bar
- Special glueing "groove" to avoid contamination of fluid path

Pipe Terminal:

- IDEX One-Piece finger-tight fitting
- Material: PEEK, pressure rating 340 bar
- For 1.6 mm tube

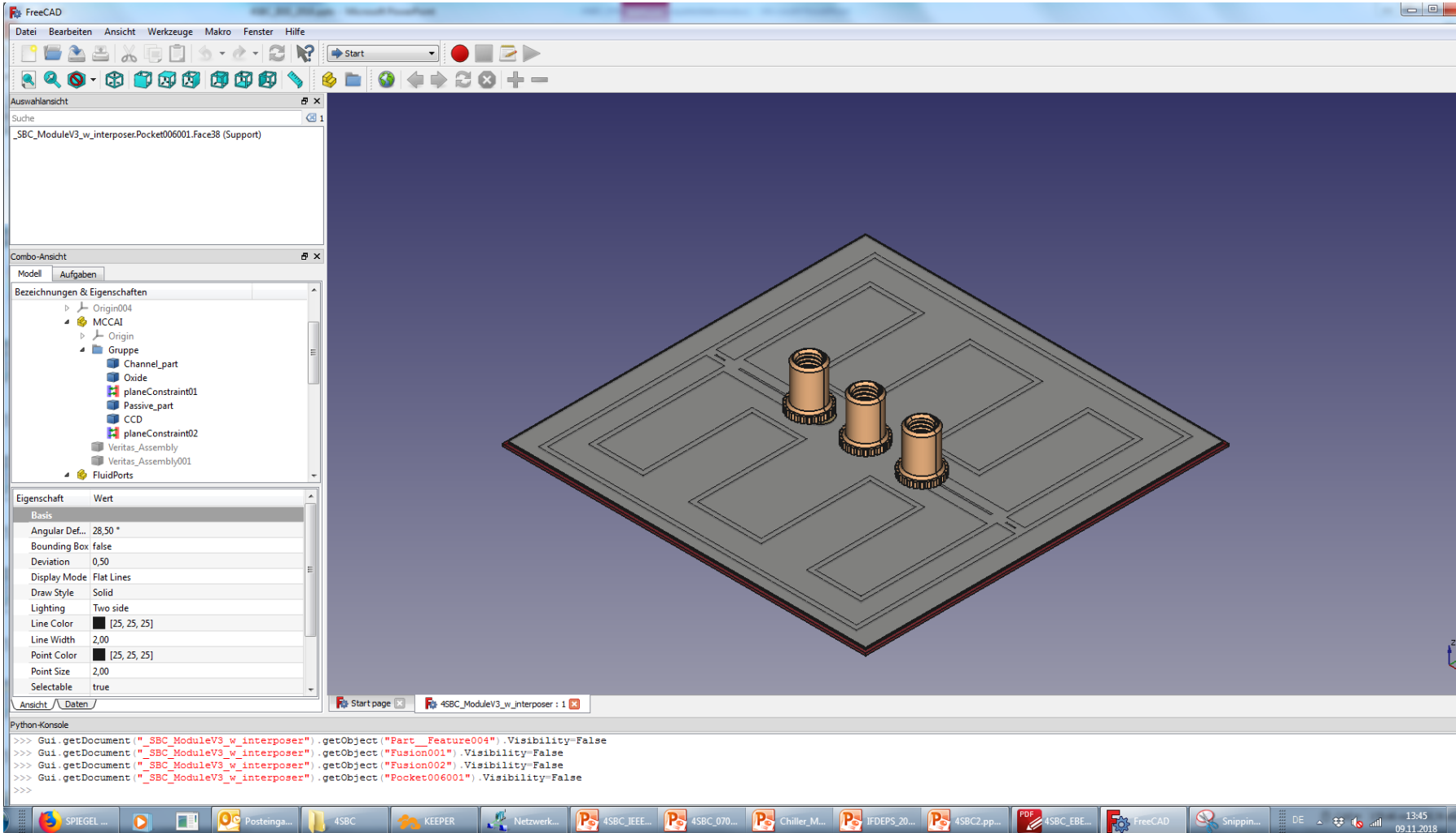
Tube:

- OD 1.6 mm, ID 0.25 – 1 mm
- Material: PEEK
- Pressure rating 480 bar
- Terminated on backend by standard (e.g. Swagelok) fittings



<http://www.vici.com/index.php>
<http://www.idex-hs.com/>

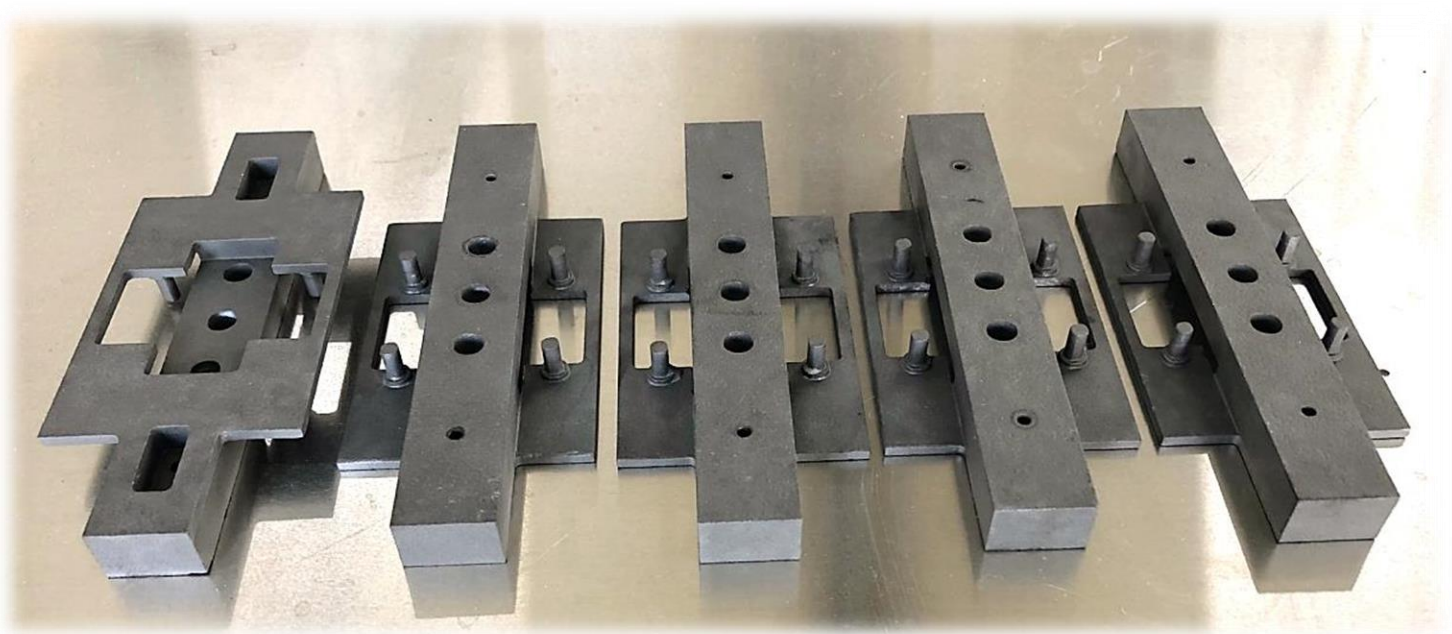
Pipes & Tubing



4SBC Pathfinder: Brackets

Support / mechanical interface:

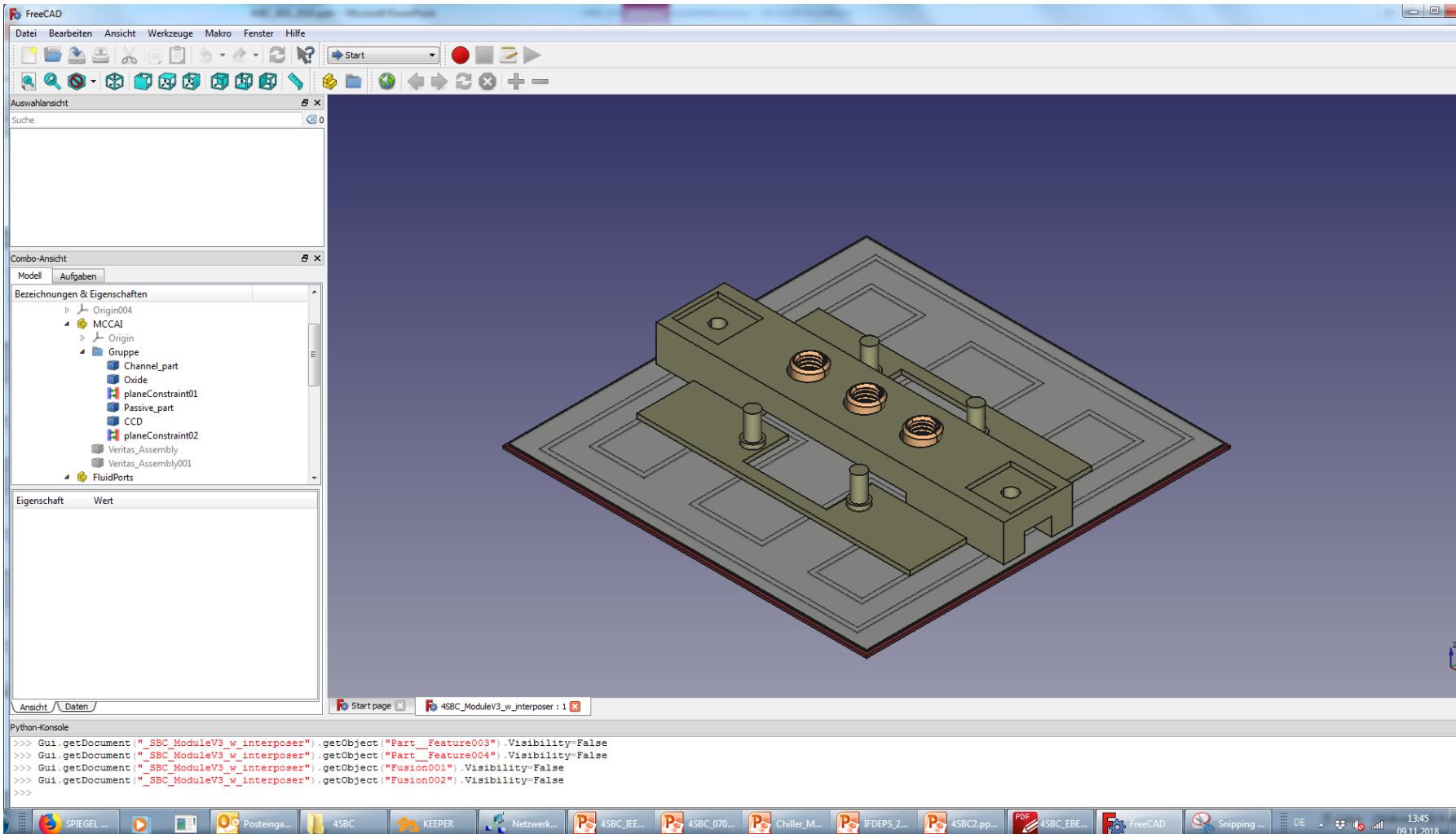
- Large-area glueing on silicon surface w/ BCB demands very good CTE match
- Here: CESIC (Carbon-Enhanced Silicon Carbide) material was selected due to
 - "Ideal" CTE match
 - Good machining properties (polishing / spark erosion of small threads...)
 - Ductility compared to Si / AlOx
 - Low thermal capacitance



CESIC sensor bracket prototypes as fired

Courtesy: M. Krödel, ECM

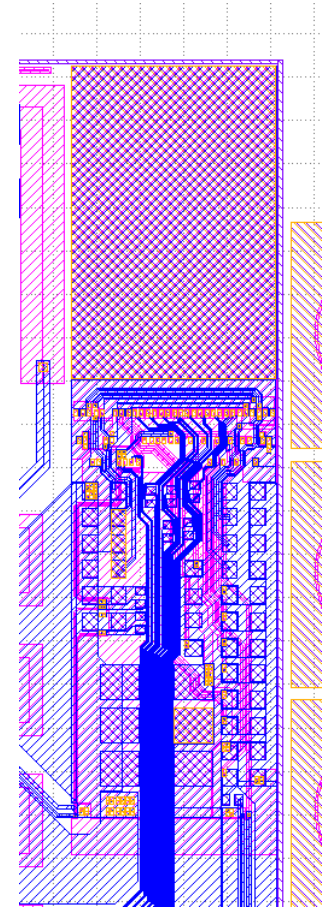
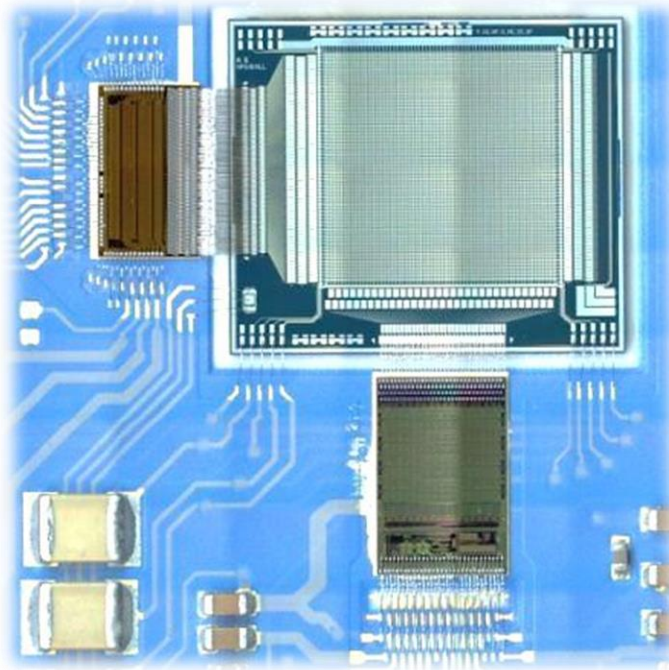
Bracket



4SBC Pathfinder: ASICs

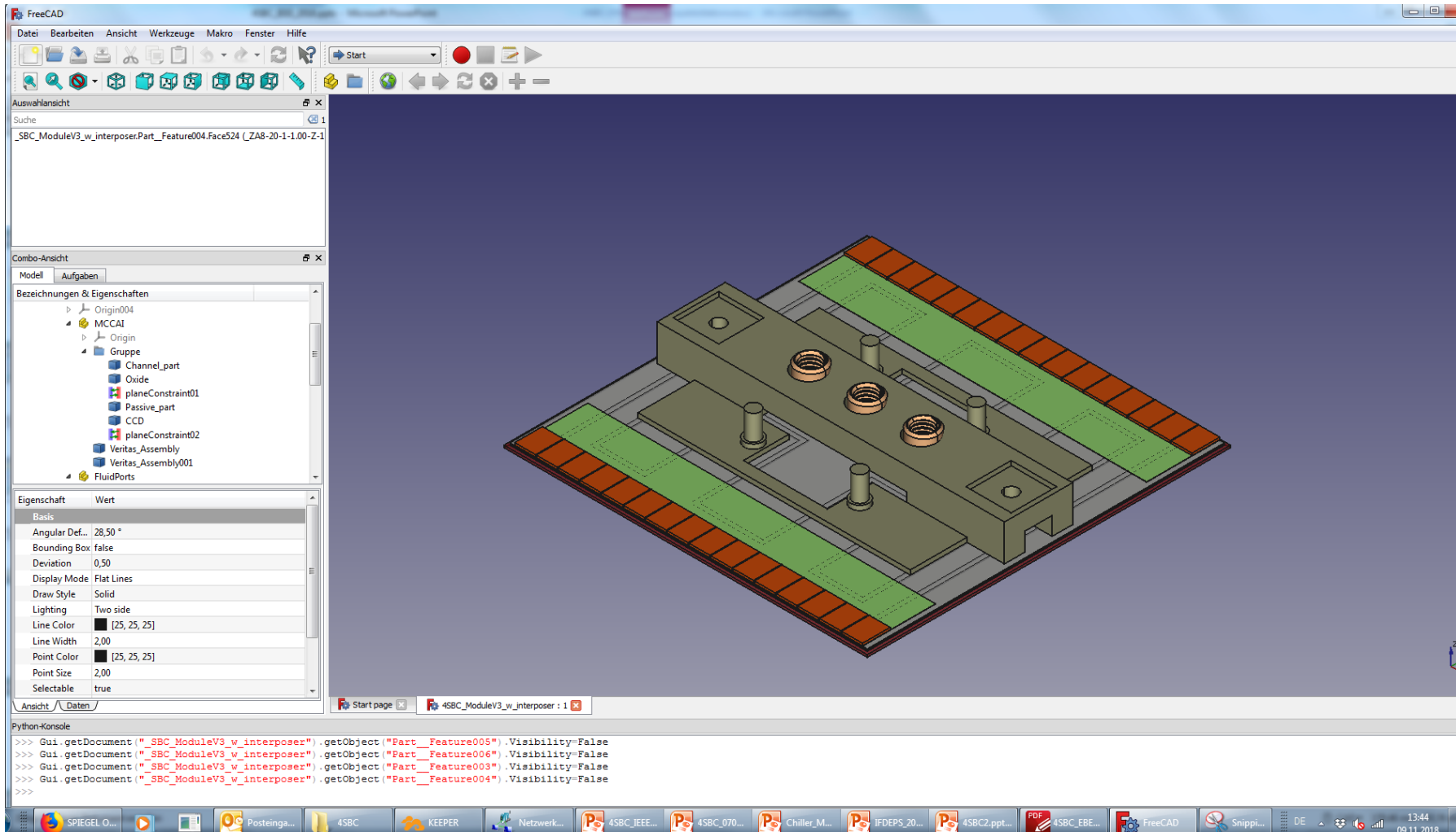
Readout IC: VERITAS II

- AMS 0.35 μ technology
- 64 channels
- Trapezoidal filter
- Fully differential architecture, CCD & DEPFET compatible
- Integrated sequencer, analog serialization ($v_{\max} = 25 - 30$ MHz)
- Min. shaping time ~ 0.5 μ s
- Noise > 1 e- ENC
- Space required for passives ~ 9.5 mm
- Targeted readout: 2.5 μ s / row
- Framerate: 800 Hz



M. Porro et al., Proc. of SPIE Vol. 9144 91445N-1 (2014)

ASICs



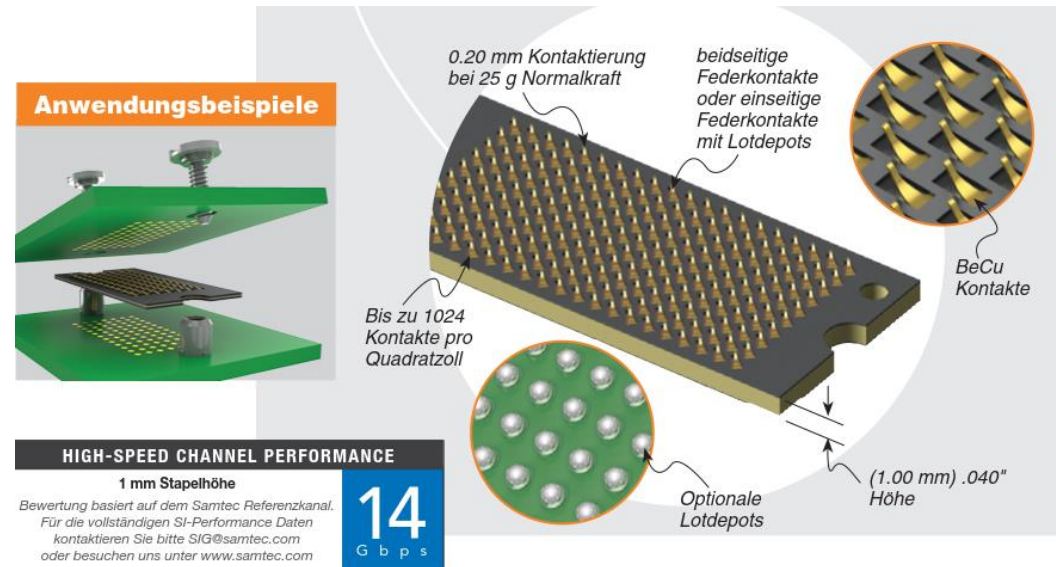
4SBC Pathfinder: Interposer

SAMTEC Z-ray interposer

- Compression-type interface
- BGA and Spring contacts
- Spring contacts for periphery
- 1 A current rating per pin
- 200 pins in total
- Tolerant against xy-displacement
- No shear forces on silicon

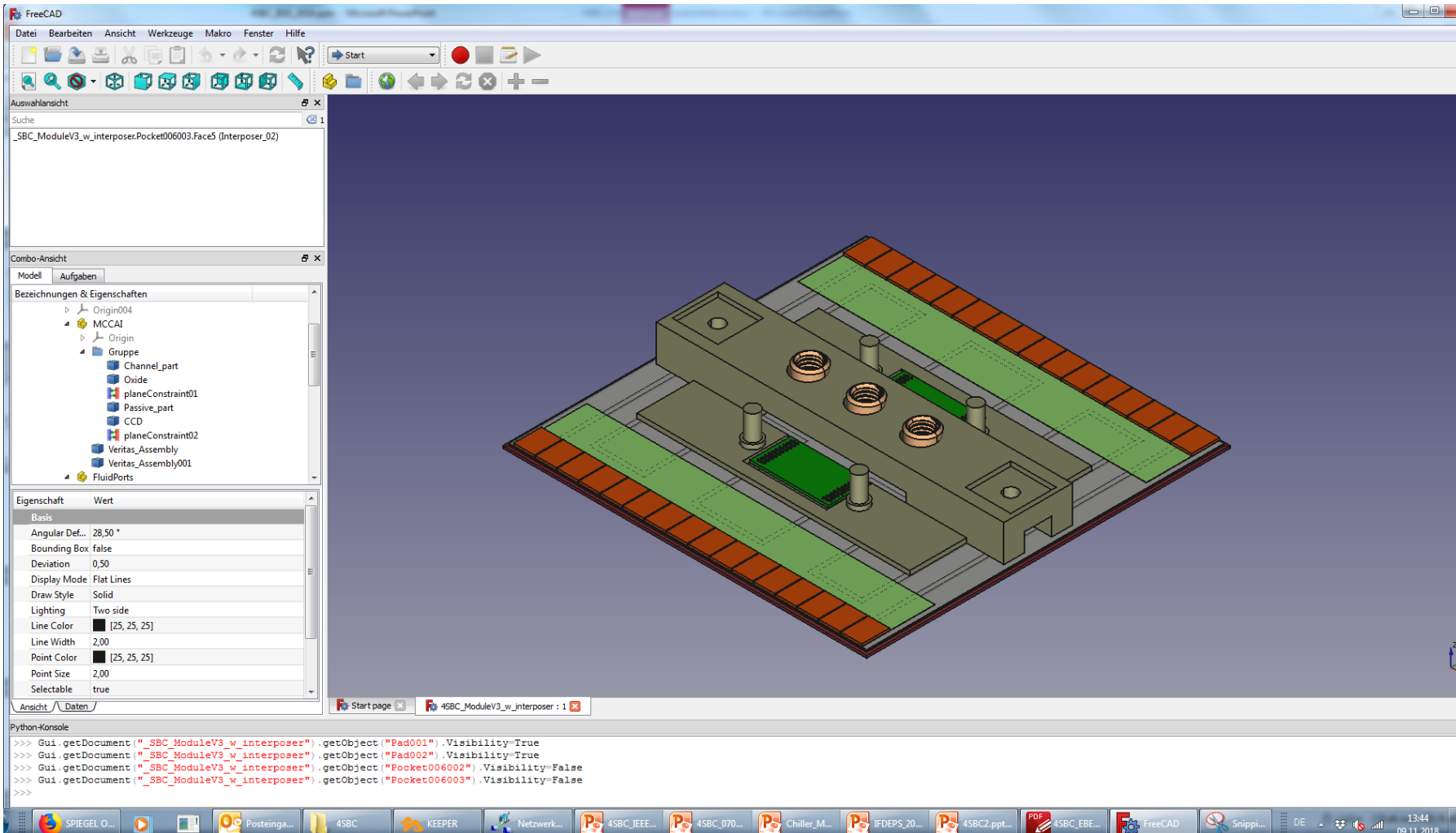
"Passive" Interposer PCB:

- Matchmaker / custom connector to backend readout electronics

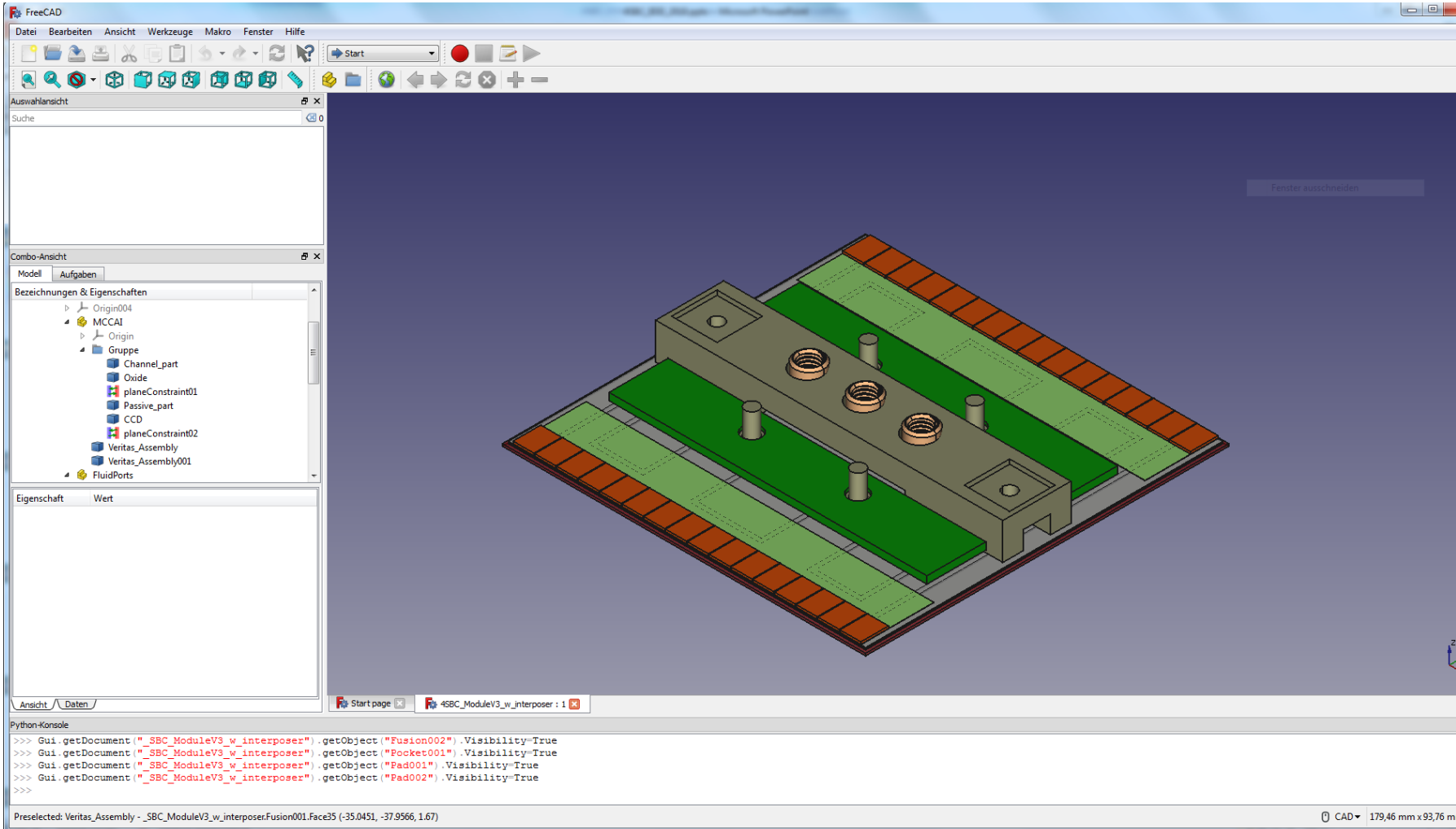


Courtesy: SAMTEC

Interposer



Interposer



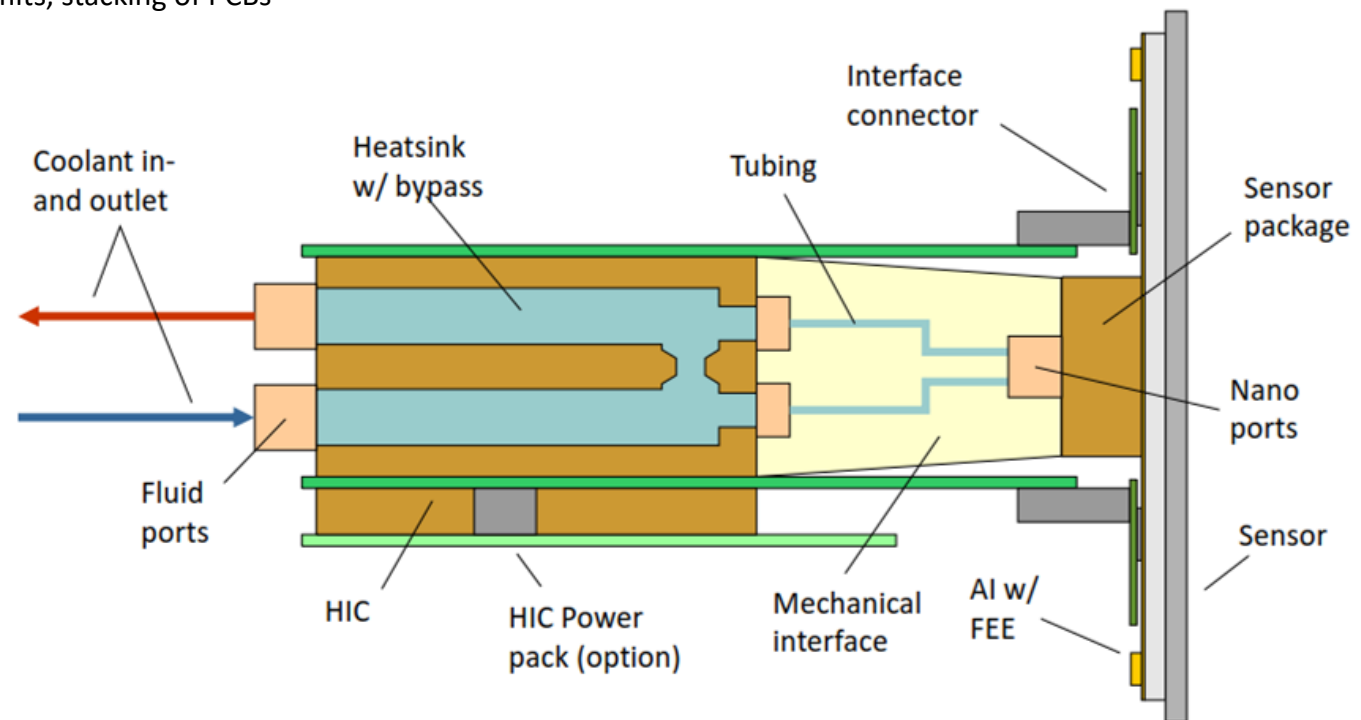
4SBC Pathfinder: Backend integration

Mechanical support

- Standard Multipin connector between interposer and Hemisphere Interface Card
- CCD connected w/ heatsink by interface parts
- Heatsink can act as pump bypass if required
- In case of PCB space limits, stacking of PCBs can be implemented
- Design in progress

Compact, flat package:

- Can easily fit in suitable vacuum compatible casing
- Low mass
- Transportable



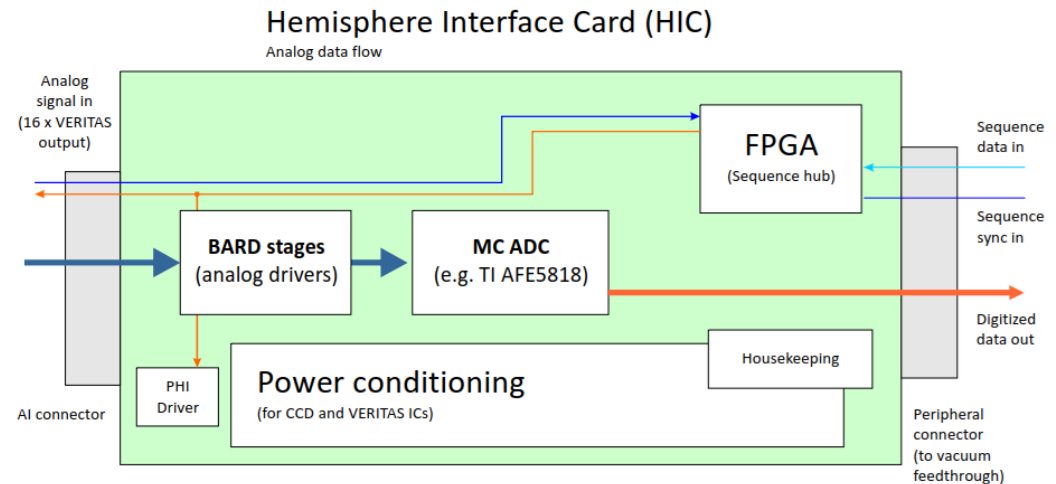
4SBC Pathfinder: Backend electronics

Hemisphere interface card

- BARD driver stages (digitally tunable)
- Multichannel ADC
- Power conditioning & housekeeping
- moved to piggy back PCB (PowerPack) if applicable
- small & simple FPGA as sequence hub

Vacuum interface:

- Only small number of voltages and digital signals to be transferred to the outside
- Required for wire length contingency



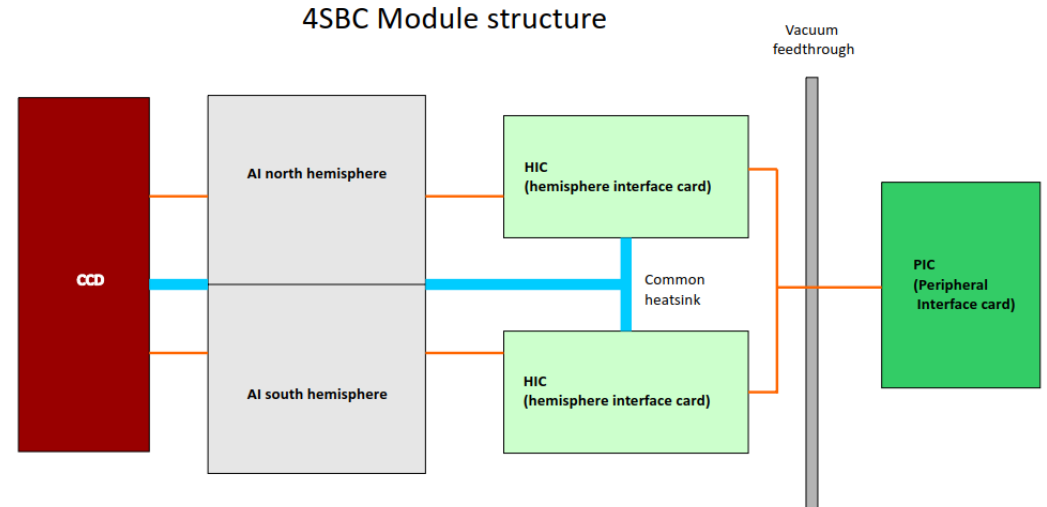
4SBC Pathfinder: System

Digital backend module

- "Brain" layer (Xilinx Zynq SoC based solution)
- Sequence generation
- Data synchronization and metadata generation
- Zero suppression & clustering
- 10 GBit Ethernet interface for data transmission to file server

Power layer:

- Prereg board to generate LDO input voltages



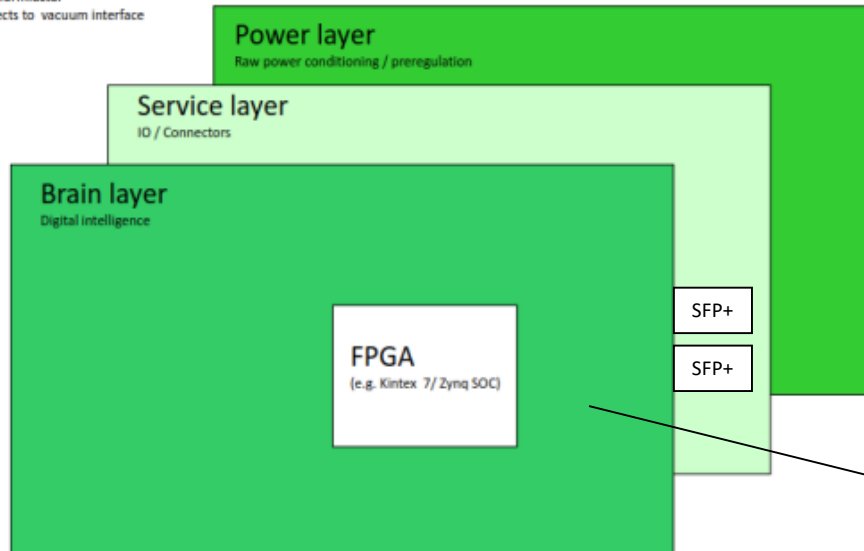
Stand-alone capability

Easy to connect to larger systems

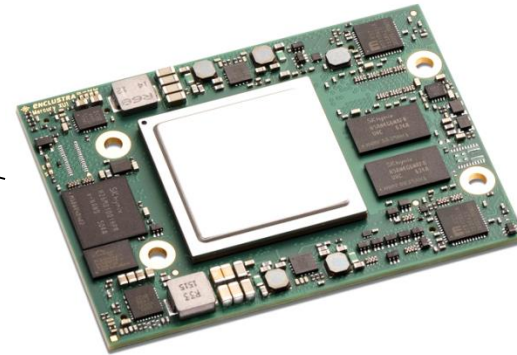
4SBC electrical backend

Peripheral Interface Card (PIC)

Stack of 3 layers
Small formfactor
Connects to vacuum interface



- Commercially available Mercury XU1+
- Xilinx® Zynq Ultrascale+™ MPSoC
- 4GB DDR4 ECC SDRAM
- 16 × 6/8/12.5 Gbit/sec MGT
- 2 × Gigabit Ethernet
- Up to 747,000 LUT4-eq
- Small form factor (74 × 54 mm)

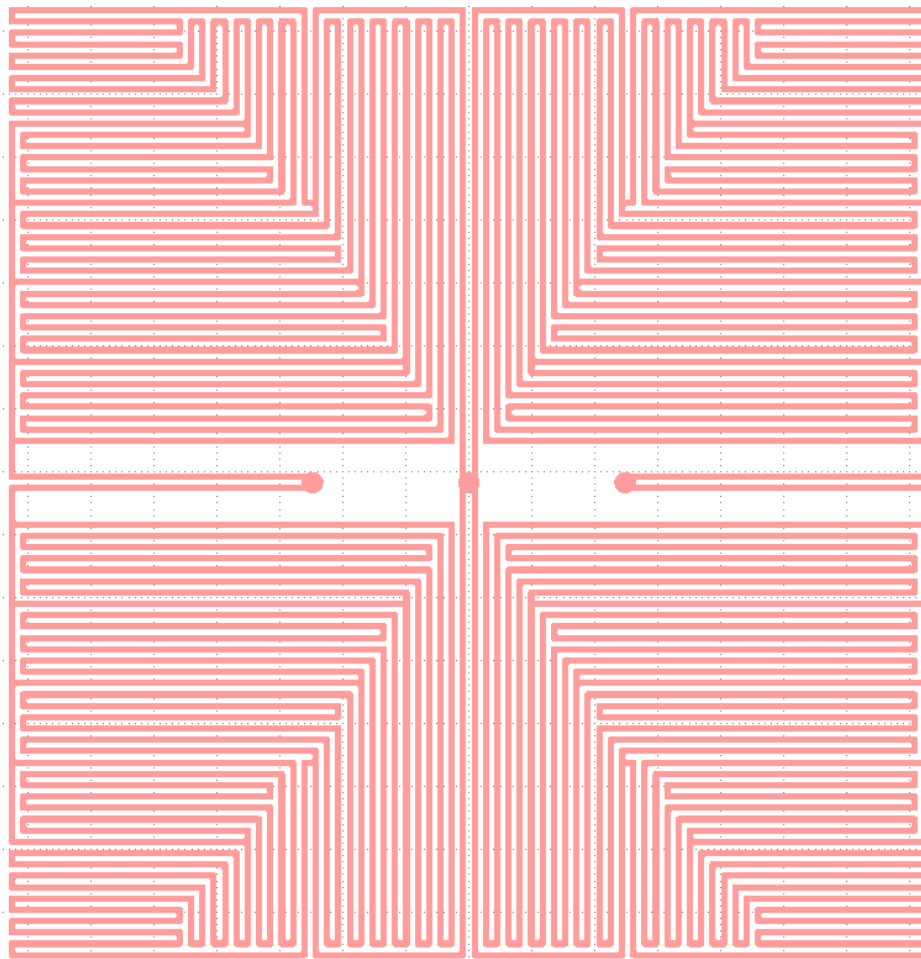


- PIC is interface to outer world and data acquisition system
- "3 layer" approach for maximum flexibility and modularity
 - "Power layer": raw supplies for HIC
 - "Service layer": offers connectivity periphery
 - "Brain layer": FPGA based preprocessor / data wrapper



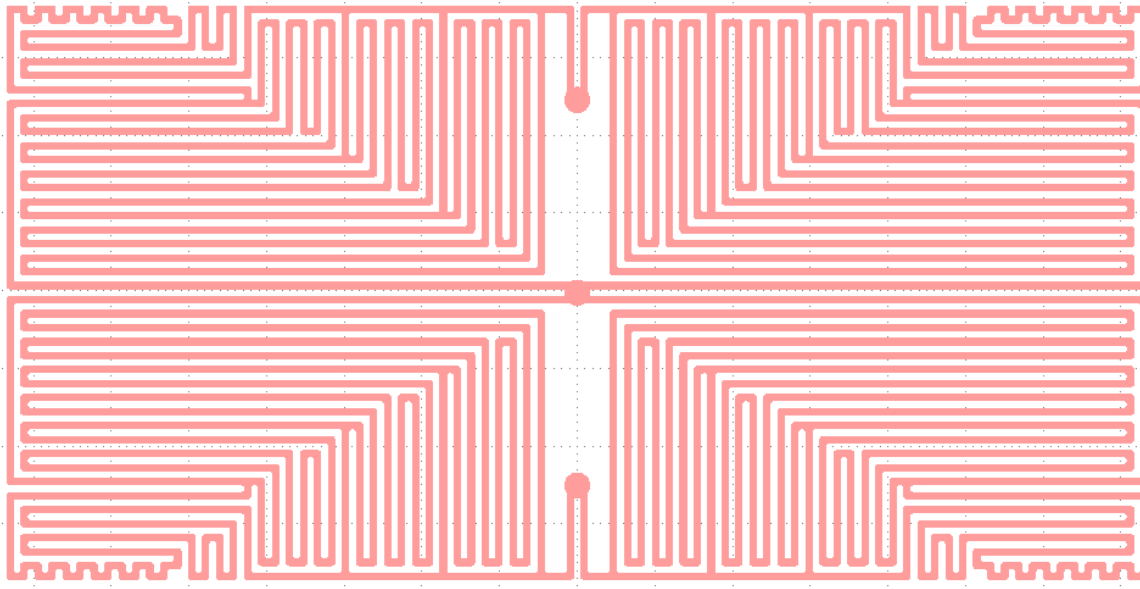
"Kids today with all their technology."

MCC production



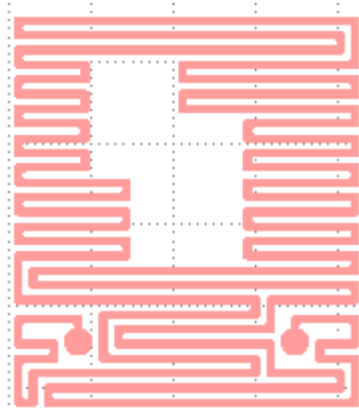
- Large area ($\sim 8 \times 8 \text{ cm}^2$) structure as base for 4SBC AI
- Performance test
- Used to furnish first prototype systems
- 4 quadrants
- 2 inlets
- 1 central outlet

FSP MCC

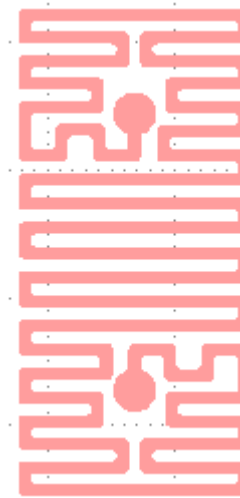


- Large area ($\sim 8 \times 4 \text{ cm}^2$) structure as replacement for the FSP Heat spreader
- 4 quadrants
- 2 inlets
- 1 central outlet
- Interfaces FSP cooling block (redesign with slight changes required)
- Lower effective length
- Optional replacement for TEC
- Eases system design and assembly
- Lower cooling requirements
- Will not have AI

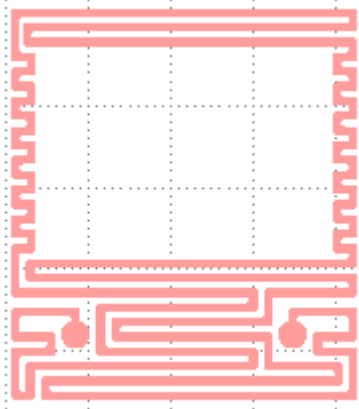
Prototype coolers



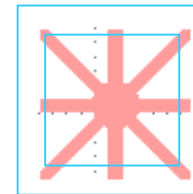
- XS MCC
- Test MCCs for DEPFET XS device sizes
- GREST hybrid etc.



- Terminal test structures
- Qualify gluing process for coolant terminals
- Check tightness, handling etc...



- MP MCC (Multipurpose)
- Test MCCs for undefined size
- Variable detector size
- Max. cutout 13 x 17 mm²
- Tradeoff flexibility vs. thermal performance
- CCD etc..

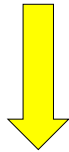


- Lid test structures
- Test structure for process of opening the access point to the MCC channels
- Contour cut opens channels at the edges to visually inspect for particle contamination

Al production

Standard dummy Material

- 450 mm material thickness
- NO embedded MCC



AI dummies:

- Test of AI layout
- Simpler technology (1 Al, 1 x Cu)
- SMD components for one ASIC
- One ASICs
- Heater structure for power deposition
- Functional verification

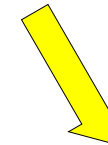
SOI raw wafers:

- 150 mm cover layer
- 300 mm channel depth
- 150 mm bottom layer



MCC heaters:

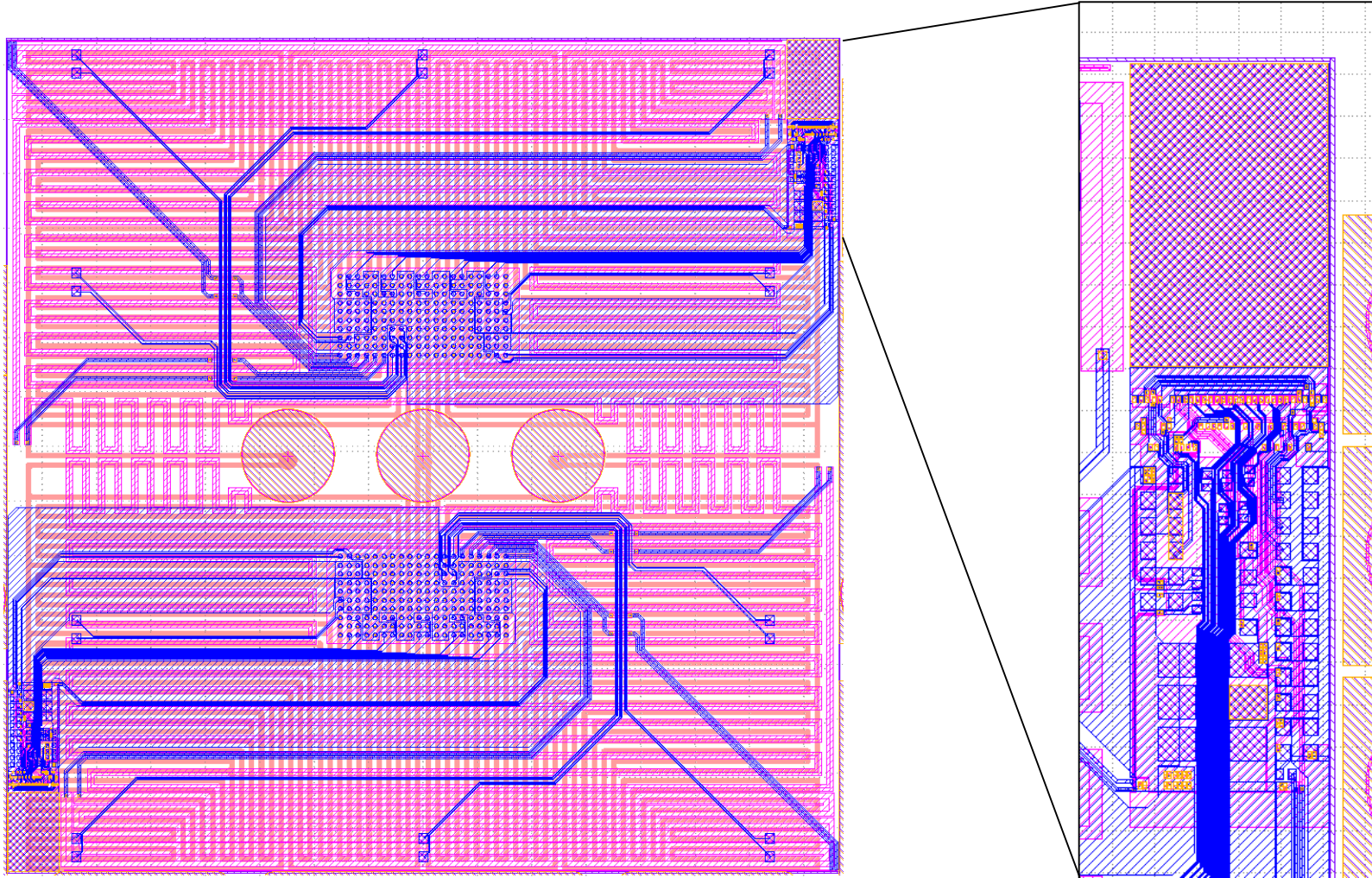
- Same layout / technology as AI dummies
- Test of MCC performance
- Test of pump equipment
- Parametrization
- Evaluation of displacement / distortion etc.
- Reliability test



AI V 1.0:

- All SMD components
- More advanced technology (2x Al, 1 x Cu)
- Fully populated with ICs
- For use with CCD

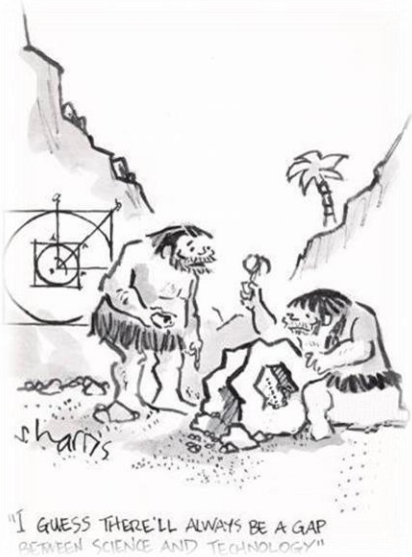
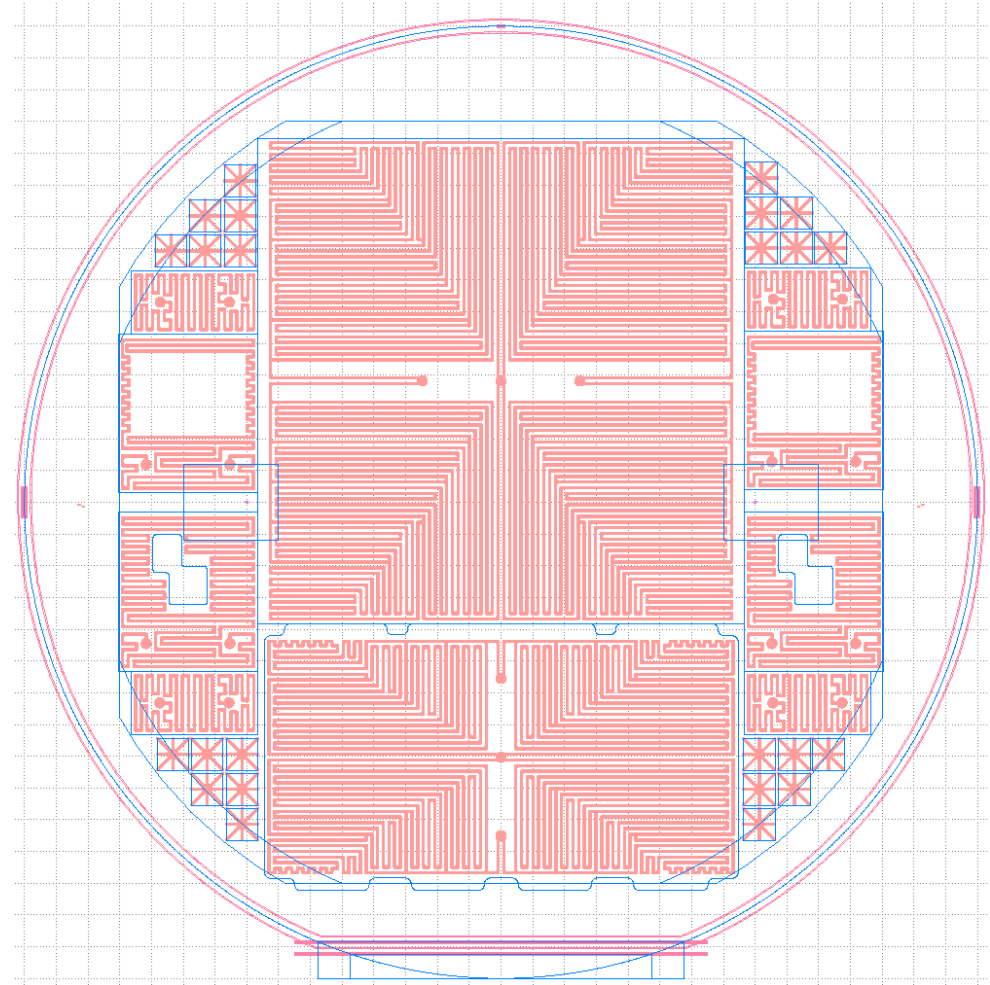
AI production



Status

AI development:

- MCC wafer layout submitted to ICEMOS
- **Scheduled delivery 10/18**
- **Postponed**
- **Date still open...**
- AI dummies in fabrication



4SBC PCU development

Pump/Chiller unit (PCU):

- Delivers required cooling power to detector at specified temperature
- Product of volumetric mass flow, density and heat capacitance
- Required pressure depends on MCC channel geometry and coolant viscosity
- **Parameters:**
 - Volumetric flow / Pressure
 - Temperature

$$\tau = \dot{v} \cdot \rho \cdot c_p$$

$$\Delta P = R_{fl} \cdot \eta \cdot \dot{v}$$

Detector

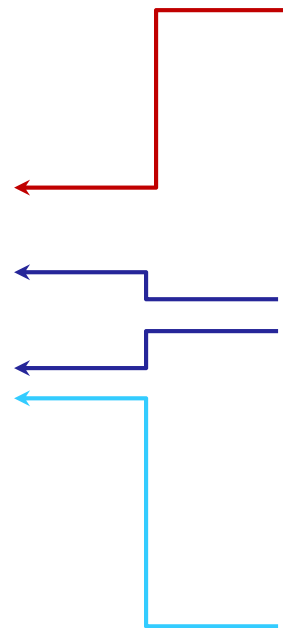
- Power dissipation
- Power distribution
- Operating temperature

Coolant

- Heat capacitance
- Density
- Viscosity
- Temperature dependence

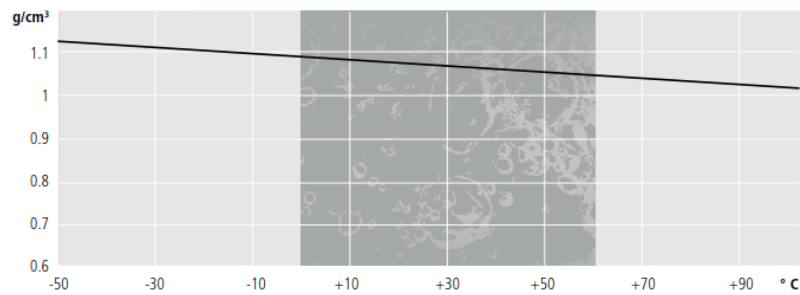
MCC

- Design
- Eff. channel length
- Channel geometry

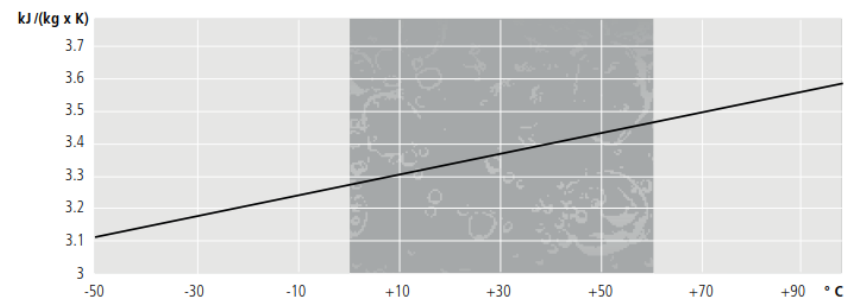


The right coolant

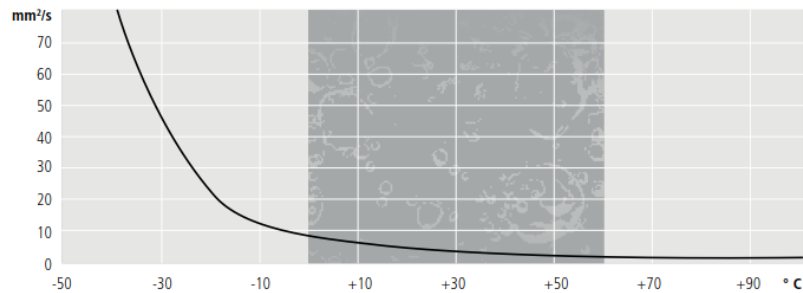
Dichte



Spezifische Wärmekapazität



Viskosität



- **Example:**
 - Data from Julabo
 - Thermal G (Water / Glycol mixture (50 : 50))

The right coolant

Class	Pro's	Con's	Comment
Silicone oil	Inert Low viscosity	Creeps "Sticky", contaminates Material limitations	Disuasion due to contamination issues
Fluorocarbons	Inert High density	Low specific heat High vapour pressure Pollute	In-house experience
Hydrocarbons	Good specific heat	Low density High viscosity Flammable Material limitations	
Glycol / water based	High specific heat High density	High viscosity Purity / composition monitoring	Excellent for high temperatures

- **Cooling requirements:**
 - Target temperature at MCC inlet ~ -40°C
 - Coolant temperature @ chiller -50 °C to - 60 °C to account for losses
 - Power dissipation per MCC ~ 6 W with low gradient

Overview

#	Fluid	Manufacturer	Material	T _{low}	Dyn. Viscosity (mPa s)		Specific heat J / (g K)		Density [g/cm ³] @ -40°C
					@20°C	@-40°C	@20°C	@-40°C	
1	DW therm	Huber	Triethoxysilan	-90°C	1.936	9.19	1.77	1.64	0.93
2	SilOil M60	Huber	Silicone oil	-60°C	4.62	23.5	1.61	1.53	0.98
3	SilOil M80	Huber	Silicone oil	-80°C	2.7	10.6	1.66	1.57	0.97
4	SilOil M90	Huber	Silicone oil	-90°C	1.74	5.64	1.76	1.65	0.96
5	Kryo 95	Lauda	Silicone oil	-95°C	1.38	5.52	1.75	1.65	0.96
6	Kryo 70	Lauda	Silicone oil	-70°C	4.6	21.3	1.52	1.45	0.97
7	Kryo 60	Lauda	Silicone oil	-60°C	2.99	12.5	1.66	1.57	0.96
8	Kryo 65	Lauda	Hydrocarbons	-65°C	1.30	8.9	2.1	1.8	0.8
9	HT135	Galden	Perfluoropolyether	-60°C	1.72	6.32	0.96	n/a	1.72
10	HT170	Galden	Perfluoropolyether	-50°C	6.04	39.1	0.96	n/a	1.77
11	HT110	Galden	Perfluoropolyether	-70°C	1.32	6.76	0.96	n/a	1.71
12	HT80	Galden	Perfluoropolyether	-80°C	0.96	3.58	0.96	n/a	1.69
13	HT70	Galden	Perfluoropolyether	-90°C	0.84	3.19	0.96	n/a	1.68
14	HT55	Galden	Perfluoropolyether	-100°C	0.74	2.45	0.96	n/a	1.65
15	Thermal HY	Julabo	Silicone oil	-80°C	< 3.6	13.4	1.5	1.45	0.96
16	Thermal H5	Julabo	Silicone oil	-50°C	5.21	22.5	1.5	1.42	0.97
17	Thermal HL60	Julabo	Silicone oil	-60°C	5.21	24.5	1.48	1.41	0.98
18	Thermal HL80	Julabo	Silicone oil	-85°C	2.86	11.5	1.7	1.55	0.96
19	Paratherm CR	Paratherm	Hydrocarbons	-88 °C	1	2	1.84	1.68	0.89
20	Paratherm LR	Paratherm	Hydrocarbons	-60 °C	3	16	1.93	1.76	0.81
21	Duratherm XLT-120	Duratherm	Hydrocarbons (?)	-85°C	0.96	4.46	2.05	1.89	0.83
22	Dynalene MV	Dynalene	Hydrocarbons	-100°C	1.07	2.63	1.80	1.59	0.892
23	PSF-1.5cSt	Clearco	Silicone oil	-80°C	1.27	5.46	1.7	n/a	0.851
24	PSF-5cSt	Clearco	Silicone oil	-70°C	4.57	37	1.63	n/a	0.918
25	PSF-10cSt	Clearco	Silicone oil	-60°C	9.35	71	1.51	n/a	0.935
26	Dowtherm J	Dow	Hydrocarbons	-80°C	1.39	2.88	1.75	1.66	0.91
27	Syltherm XLT	Dow	Silicone oil	-100°C	1.4	> 3.1	< 1.83	< 1.69	0.9
28	Syltherm HF	Dow	Silicone oil	-73°C	1.7	12	1.71	1.48	0.92
29	Dowtherm 4000	Dow	Glycol-based	-50°C	4.5	44	3.21	3.05	1.11
30	Dowtherm SR-1	Dow	Glycol-based	-50°C	4.5	44	3.29	3.09	1.1
31	HFE-7100	3M	Hydrocarbons	~ -80°C	3	16.3	1.17	1.05	1.63

Examples for all classes

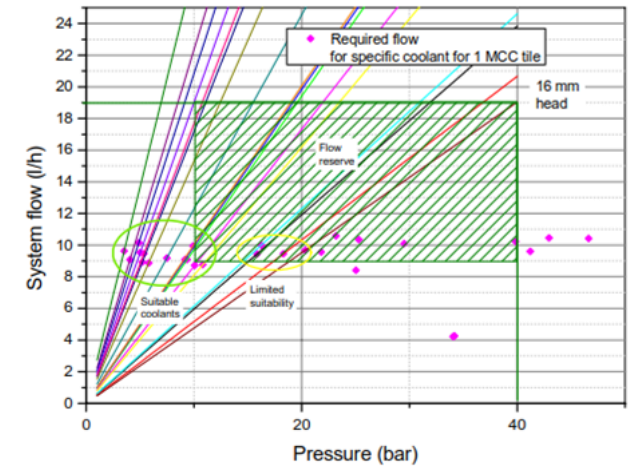
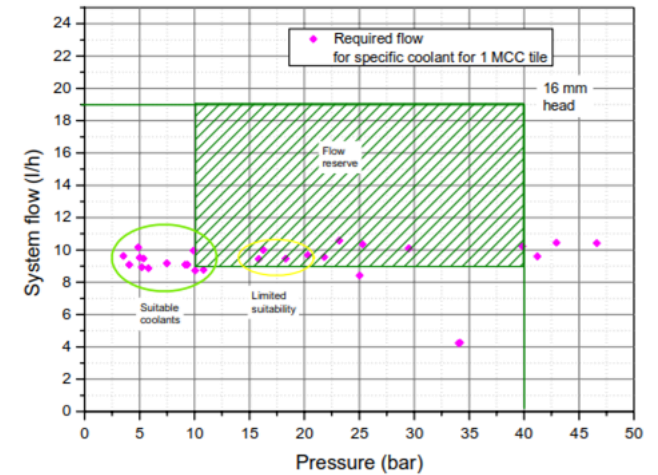
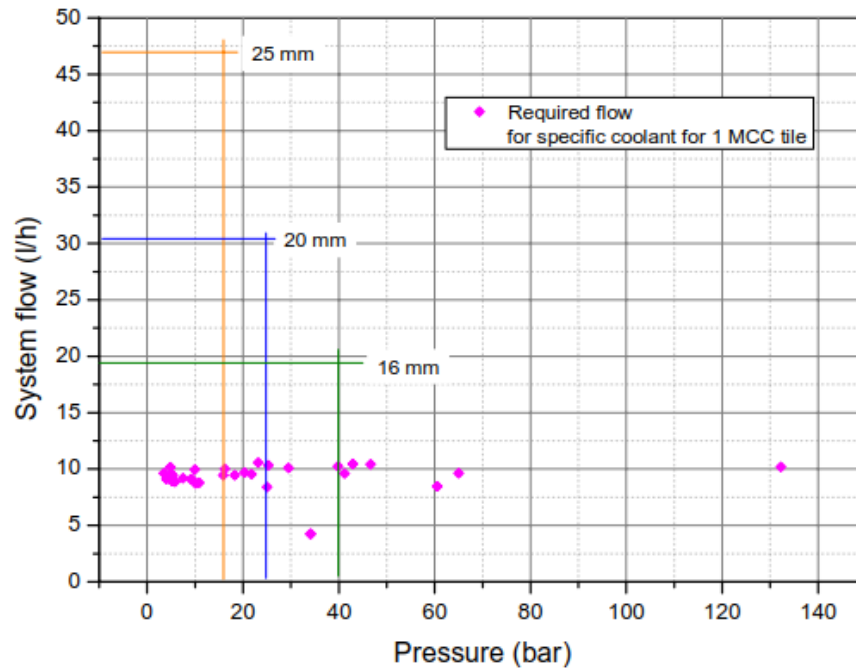
Available on the market in suitable quantities

Probably there are more...

Chosen coolant has big impact on required pump / chiller system!

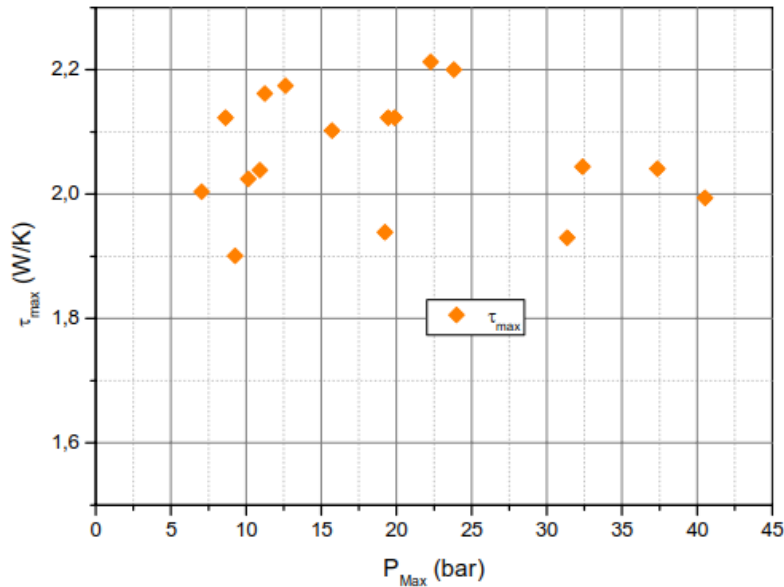


Pump vs. coolant



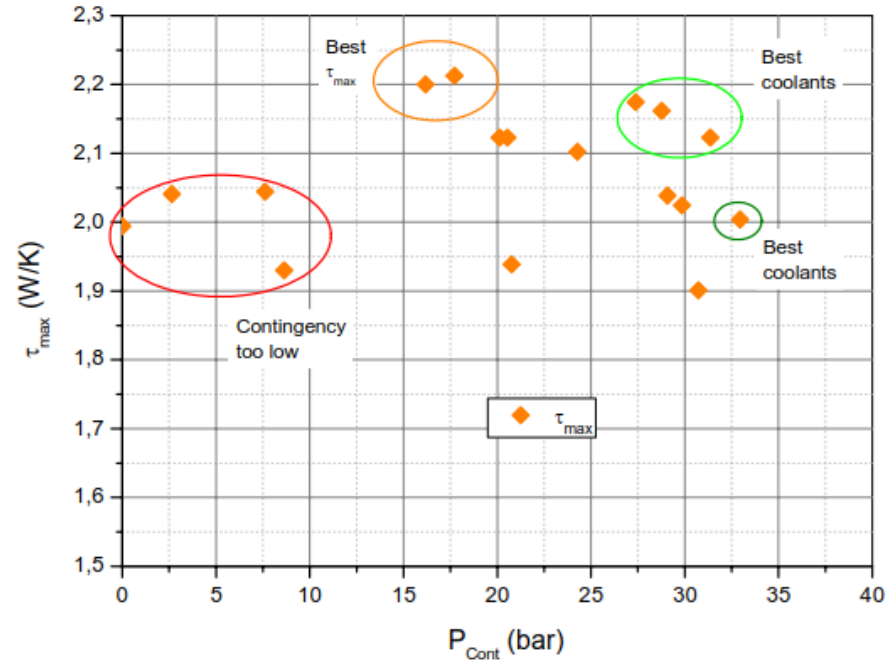
Example:
Lewa FC metering pump line

Pump vs. coolant II



Contingency:

- High pressure contingency required
- Compensate flow-dependent pressure drop on pipework
- Best medium is high achievable τ_{max} for max. contingency
- Pump-dependent



Pump vs. coolant III

#	Fluid	Manufacturer	Material	Ref. flux [l/h]	Ref. pressure [bar]	P_{Max} [bar]	τ_{max} [W/K]	P_{Cont} [bar]	Evaluation
1	DW therm	Huber	Triethoxysilan	2,4	16	32	2,0	8	Contingency too low
3	SilOil M80	Huber	Silicone oil	2,4	18	37	2,0	3	Contingency too low
4	SilOil M90	Huber	Silicone oil	2,3	10	20	2,1	20	
5	Kryo 95	Lauda	Silicone oil	2,3	9	20	2,1	20	
8	Kryo 65	Lauda	Hydrocarbons	2,5	16	31	1,9	9	Contingency too low
9	HT135	Galden	Perfluoropolyether	2,2	10	22	2,2	18	Best $\tau_{u,max}$
11	HT110	Galden	Perfluoropolyether	2,2	11	24	2,2	16	Best $\tau_{u,max}$
12	HT80	Galden	Perfluoropolyether	2,2	6	13	2,2	27	Best
13	HT70	Galden	Perfluoropolyether	2,2	5	11	2,2	29	Best but high vapour pressure
14	HT55	Galden	Perfluoropolyether	2,3	4	9	2,2	31	Best but high vapour pressure
18	Thermal HL80	Julabo	Silicone oil	2,4	20	40	2,0	0	No contingency
19	Paratherm CR	Paratherm	Hydrocarbons	2,4	4	7	2,0	33	Best contingency
21	Duratherm XLT-120	Duratherm	Hydrocarbons (?)	2,3	8	16	2,1	26	
22	Dynalene MV	Dynalene	Hydrocarbons	2,5	5	9	1,9	31	
23	PSF-1.5cSt	Clearco	Silicone oil	2,5	10	19	1,9	21	
26	Dowtherm J	Dow	Hydrocarbons	2,4	5	10	2,0	30	
27	Syltherm XLT	Dow	Silicone oil	2,4	5	11	2,0	29	

Result:

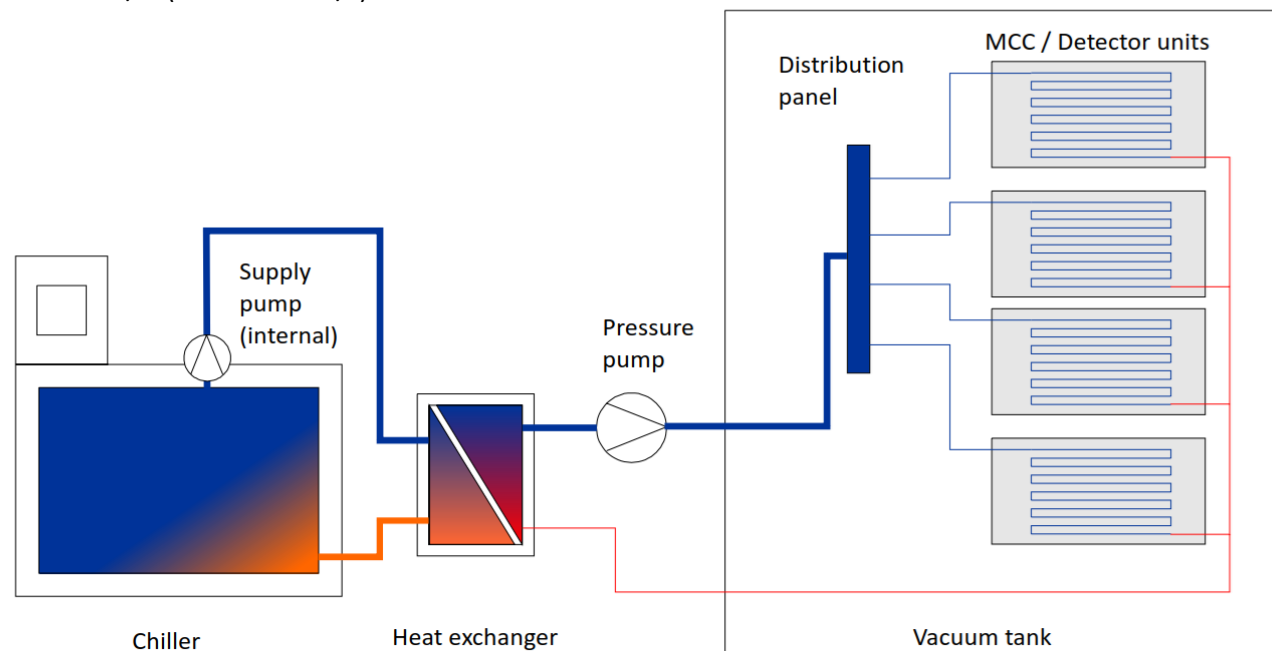
- Fluorocarbons win (for this pump...)
- Low viscosity, low operating temperature



4SBC Pathfinder: Pump system

Chiller unit:

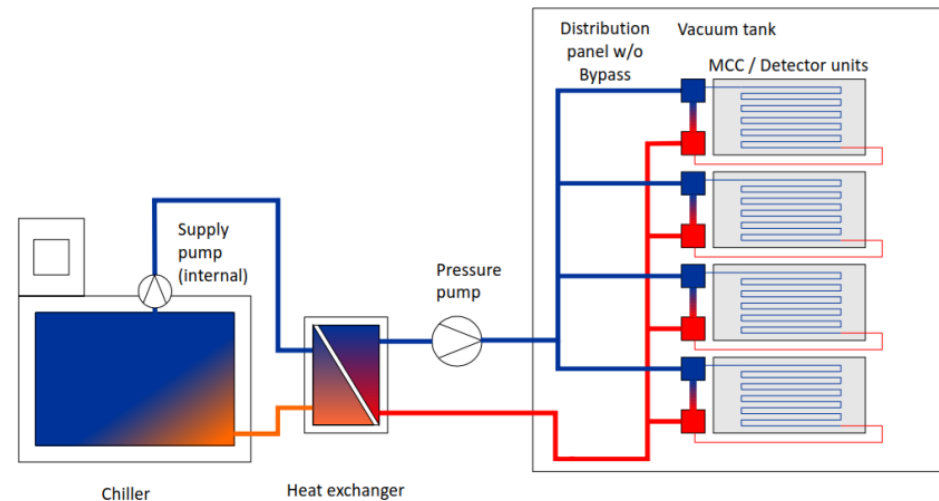
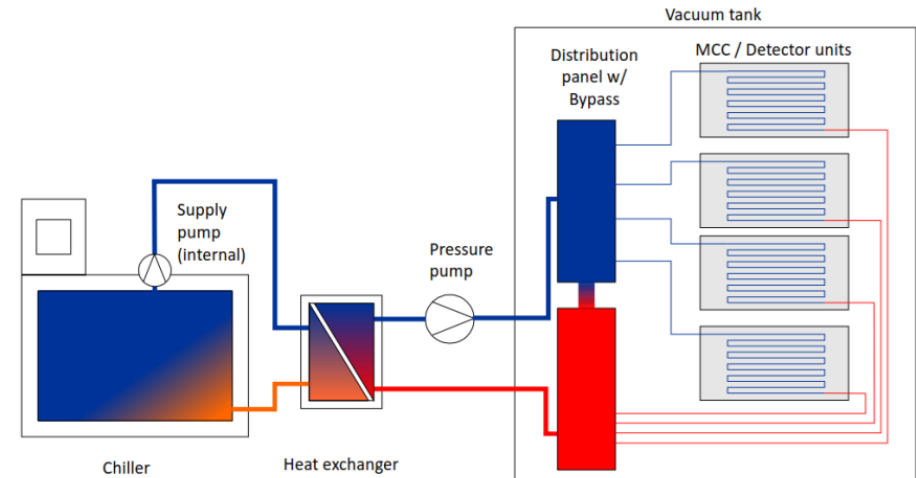
- System adequate for 4 4SBC modules
- Temperature at inlet of MCC -40°C
- Min. Chiller temperature ~ -60 °C
- Cooling power ~ 25 - 30 W per module (including contingency)
- Total cooling power ~ 120 W (plus some overhead for losses)
- Target flow **in MCC** min / max ~ 10 - 40 l / h (2.8 – 11.1 ml/s) including contingency
- Target pressure range 25 – 30 bar including contingency
- Short distance to pressure distribution panel (< 10 cm), bridged with 1 mm inner Ø pipes
- Compact, as small form factor as possible
- Flow measurement possible
- Low pulsation (snubber?)



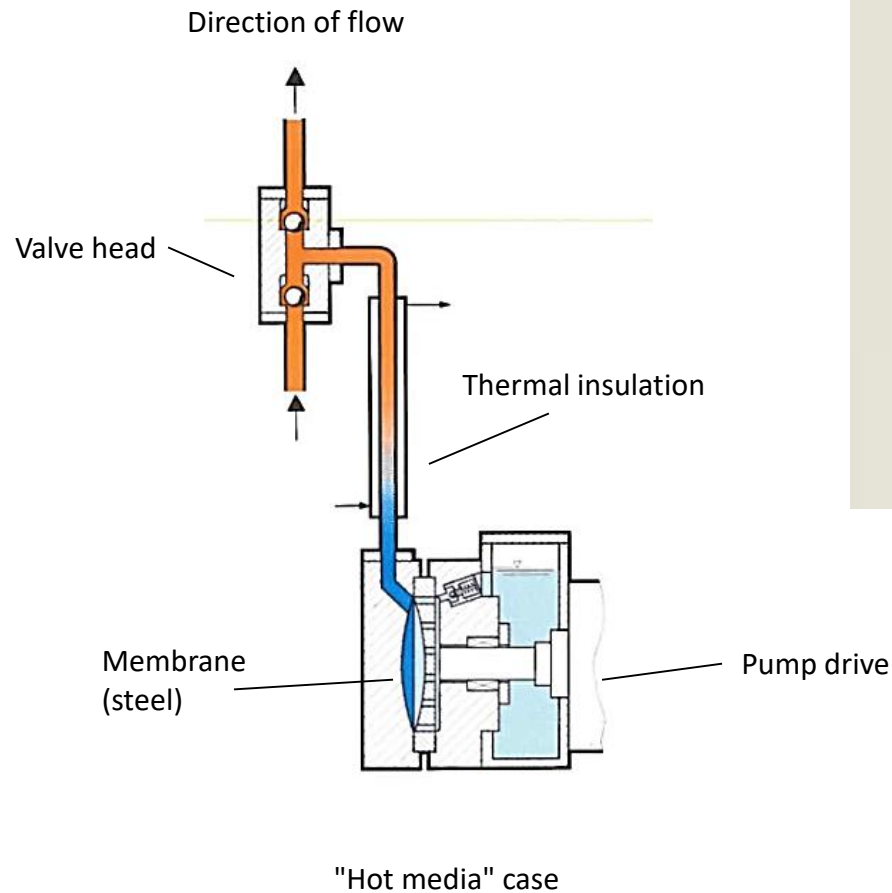
4SBC Pathfinder: Pump system

Problem: Long pipes!

- Thermal losses in pipe system
- **Large pipe diameters:**
 - Low pressure overhead
 - Small exchange rate
 - Big impact on system losses
- **Small pipe diameters**
 - High pressure overhead
 - Large exchange rate
 - Big impact on system safety
- **Suggestion:**
 - Implement bypass
 - Large pipe diameters
 - Large exchange rate
 - low pressure overhead
 - overall flow around 10 x MCC flow
 - Reevaluation of pump concept required



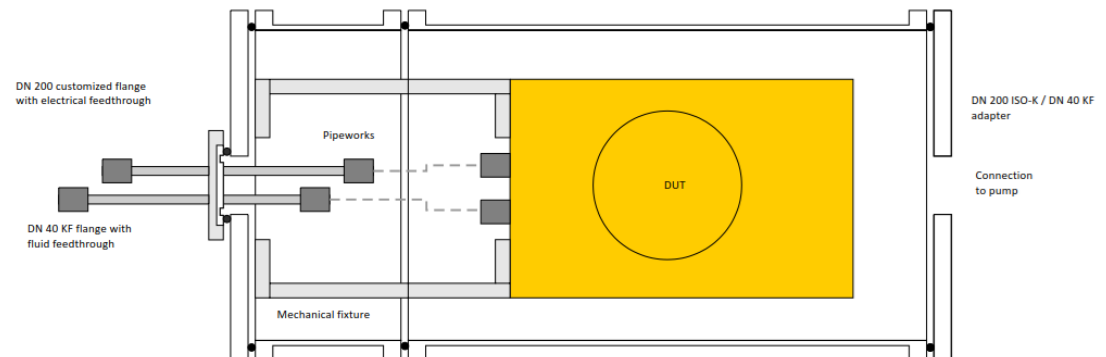
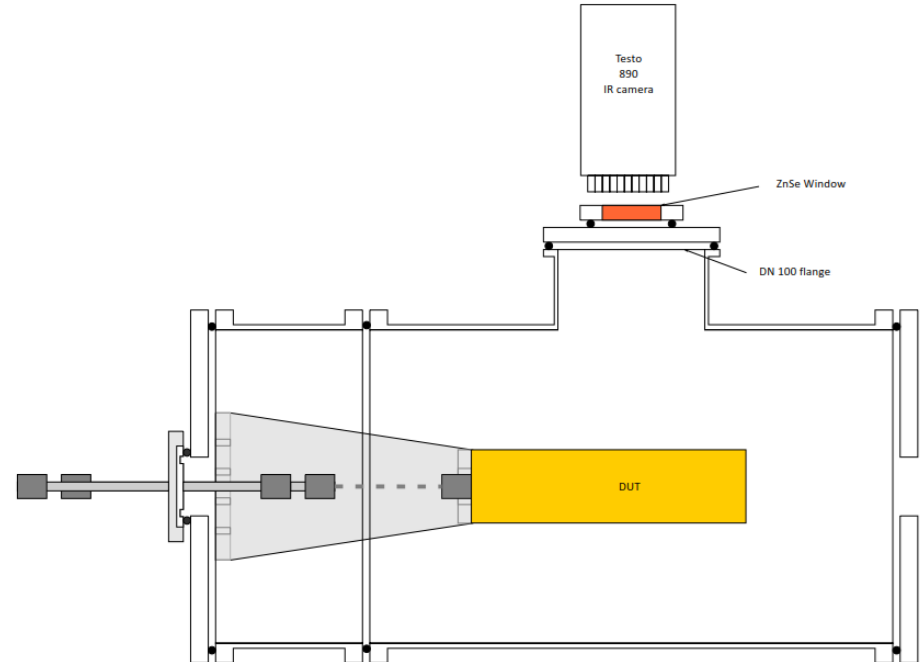
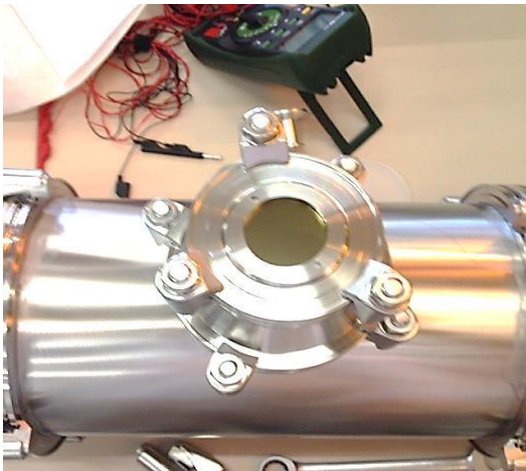
4SBC Pathfinder: Pump concept



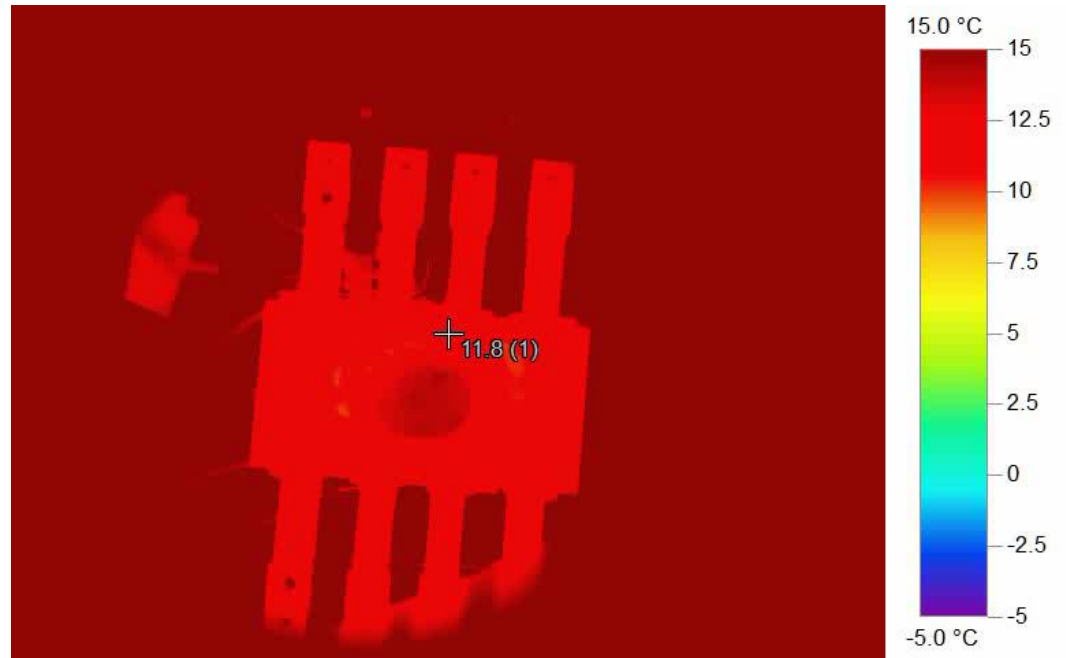
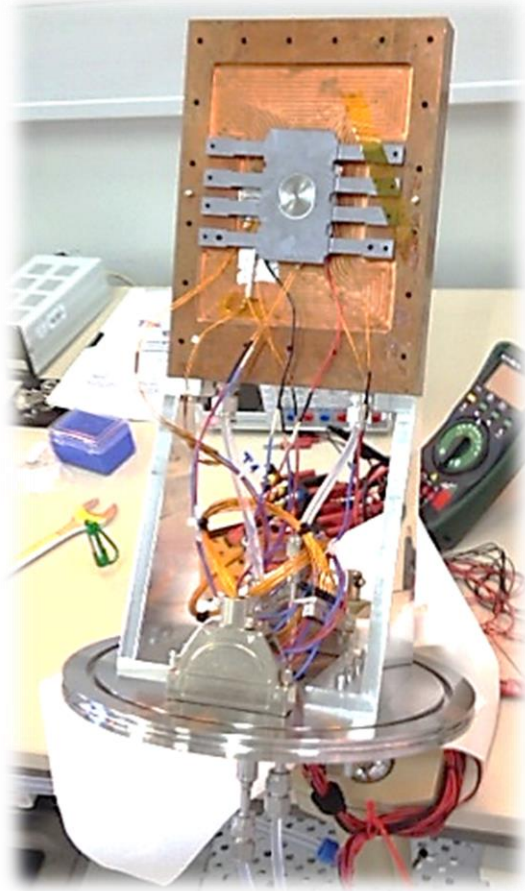
Pump:

- LEWA Eco line series
- Provide sufficient flow for bypass
- Hydraulic coupling
 - limits heat intake
 - prevents cooldown of pump drive below operating temperature range
 - Possible "active cooling" of link

Thermal test setup



Thermal test setup



Outlook

CCD production

- In progress
- Ready mid '19

MCC development

- In progress
- **Waiting for SOI delivery**
- Evaluation of prototype required

AI development

- In progress
- **Waiting for AI dummies**
- **Waiting for SOI delivery**

PCU development

- Back to square one
- Bypass required
- Implement simple solution for prototype evaluation

Additional activities:

- Adaption of electronics
- Through-Silicon Vias
- Tooling / Test facilities
- Glueing / mounting processes

Biggest issue:
Availability of SOI
base material!



Status

----- Weitergeleitete Nachricht -----

Betreff:RE: Request for 2019

Datum:Tue, 19 Feb 2019 15:06:07 -0000

Von:Hugh Griffin <hughgriffin@icemostech.com>

An:lca@hll.mpg.de

Hello Laci,

Unfortunately i do not have positive news to share with you.

The operations team are working through a large backlog of orders from 2018 as well as planning what is already a full order book for 2019.

The IceMOS factory is at full capacity.

The team are working to re-plan the production and shipping schedule and we will be issuing revised order confirmation/delivery dates to customers as soon as possible.

I do apologise that I cannot offer better news at this time.

Sincerely,
Hugh

Thanks for your attention

Questions?

